



*Evaluation of non-Rutherford alpha elastic
scattering cross-sections for silicon*

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***¹On leave from :-
Institute of Physics & Power Engineering, Obninsk, Russia***



Acknowledgements

The **Leverhulme Trust** :- Visiting Professorship for A.F.Gurbich:
also colleagues at Surrey: **Jeff Tostevin** & **Ed Simpson** exploring
complementary use of SigmaCalc (Gurbich) and AZURE (Azuma++)

IAEA for supporting IBANDL and SigmaCalc
www-nds.iaea.org/ibandl & www-nds.iaea.org/sigmacalc

Engineering & Physical Sciences Research Council (**EPSRC**, UK) for
supporting the EBS measurements made in September 2005
(grant GR/R 50097)

The **Royal Society** (UK) for funding A.F.Gurbich's visit to Surrey in 2005

This work has been supported by the European Community as an
Integrating Activity «Support of Public and Industrial Research Using Ion
Beam Technology (**SPIRIT**)» under EC contract no. 227012

Contents

- Introduction – Materials Analysis
- The $^{28}\text{Si}(\alpha, \alpha)^{28}\text{Si}$ reaction
- Summary

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 - *Surrey Ion Beam Centre*
 - Materials Modification by Ion Implantation
 - Thin Film Depth Profiling by Ion Beam Analysis
 - *Ion Beam Analysis Overview*
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 - Nuclear Excitation – RBS, EBS, ERD, NRA
 - Scanning microbeam, channelling, external beam
 - *PIXE + Backscattering – self-consistent analysis*
 - *Accurate analysis!*
- The $^{28}\text{Si}(\alpha, \alpha)^{28}\text{Si}$ reaction
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Controllable Materials Modification

- **Facilities**

- *0.4-2MV High Energy Implanter (1991)*
- *2-200kV High Current Implanter (1997)*
- *Implantation 2keV $\Rightarrow$ 4MeV (up to 10mA)*
- *Sample size $\frac{1}{4}\text{mm}^2$ to $\frac{1}{4}\text{m}^2$*
- *Hot (1000°C) or cold (~LN & 10K)*
- *Sample chambers in class 100 clean room*

- **Applications**

- *Ion Beam Synthesis*
 - Buried and surface oxides, silicides etc
- *Ion Implantation*
- *Defect Engineering*
- *Proton beam lithography (using Tandem)*
 - potentially nm resolution to 10 μm depths



IBA equipment at Surrey

- 2 MV Tandem
 - Installed & commissioned 2002
 - up to: 4 MeV $^1\text{H}^+$; 6 MeV $^4\text{He}^{++}$; 12 MeV $^{197}\text{Au}^{5+}$
 - -ve beam injection
 - duoplasmatron source good for H^- , He^+
 - For He^- use Li vapour charge exchange
 - Nitrogen gas stripper at HV terminal
 - Pressure vessel SF_6 at 6.5 bar
- 5 beam lines
 - Microbeam ($1 \times 1 \mu\text{m}$); nanobeam ($30 \times 30 \text{ nm}$??)
 - Broad beam ($100 \times 100 \mu\text{m}$); external beam ($50 \times 50 \mu\text{m}$); PIGE/PINE line
 - Vertical beam line for radiation biology ($500 \times 500 \text{ nm}$)
 - 6-axis goniometer: 100 x 150 mm stage



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Ion Beam Analysis Methods

RBS

Energy of scattered protons or He
give light element composition and
elemental depth profiles

0.2 – 4 MeV protons
or 0.2 – 6 MeV He⁺⁺
or 0.2 – 12 MeV Au⁵⁺
or 3He (or D?) etc

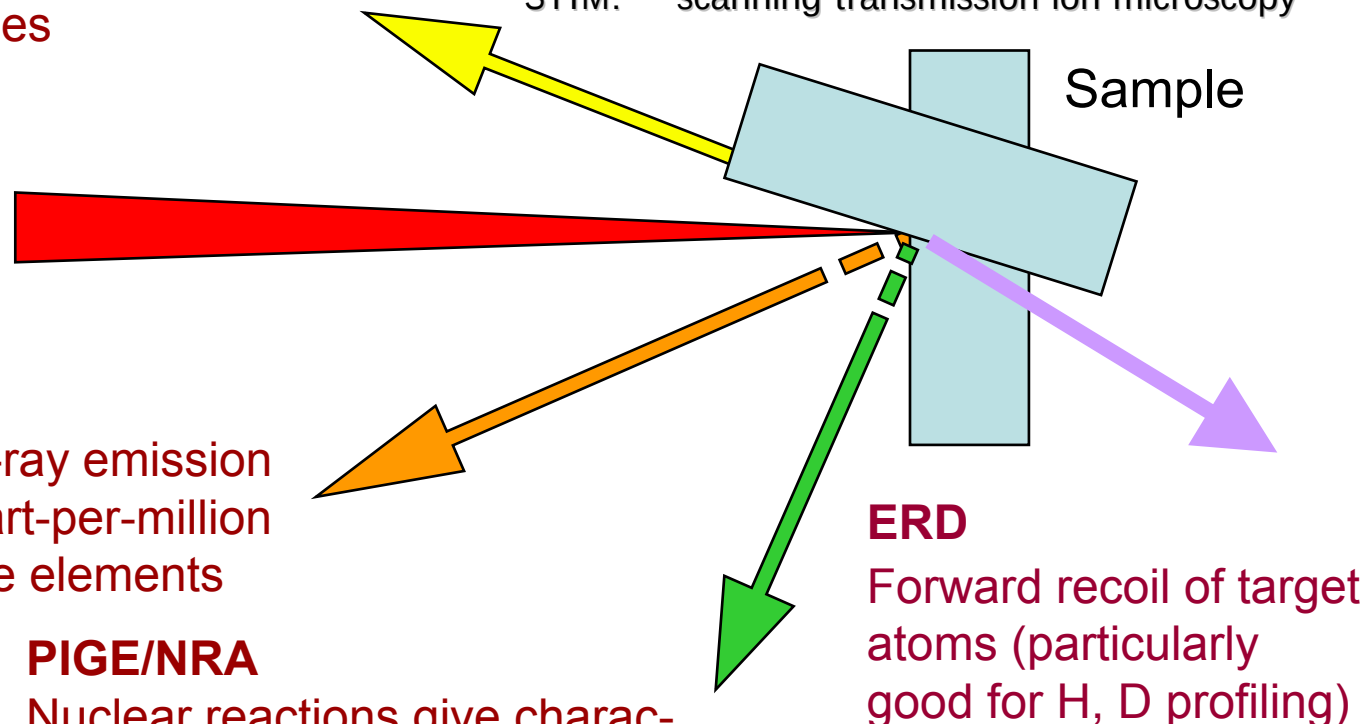
PIXE

Characteristic X-ray emission
Simultaneous part-per-million
detection of trace elements
from Na to U

PIGE/NRA

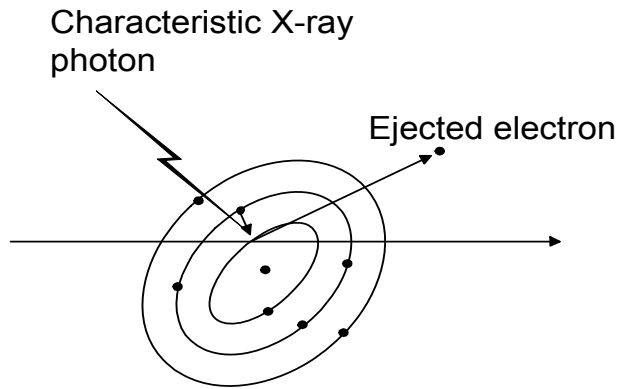
Nuclear reactions give charac-
teristic gamma rays and/or particles
from light nuclei (e.g. Li, B, F)

IBIL: ion beam induced luminescence
IBIC: ion beam induced current
STIM: scanning transmission ion microscopy

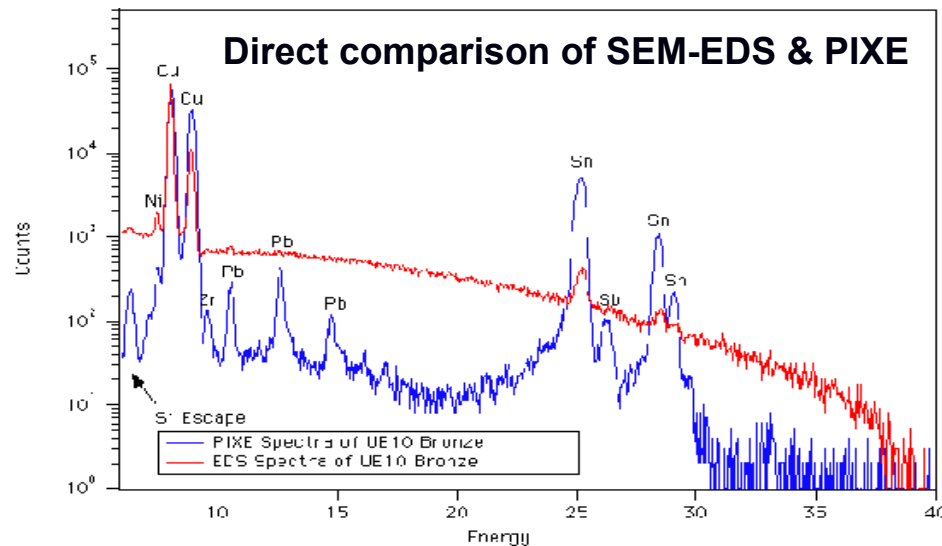


- Atomic excitation
 - *PIXE (particle-induced X-ray emission)*
 - As for SEM-EDX or EPMA (electron excitation), XRF (X-ray excitation)
 - High cross-sections relative to nuclear excitation
- Nuclear excitation
 - *Particle elastic scattering (RBS, EBS, ERD)*
 - Rutherford scattering (Coulomb potential, point charges)
 - non-Rutherford scattering (Schrödinger's equation, elastic exit channel)
 - *Particle nuclear reactions (NRA, PIGE)*
 - Schrödinger's equation, inelastic exit channel
 - eg. $^{27}\text{Al}(p,\gamma)^{28}\text{Si}$, $^{11}\text{B}(\alpha,p_0)^{14}\text{C}$,
 - $^{15}\text{N}(p,\alpha_0)^{12}\text{C}$ and $^1\text{H}(^{15}\text{N},\alpha_0)^{12}\text{C}$ are inverse reactions
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 - $^{14}\text{N}(d,\alpha_0)^{12}\text{C}$, $^{14}\text{N}(d,\alpha_1)^{12}\text{C}$, $^{14}\text{N}(d,p_0)^{15}\text{N}$ are all evaluated
- Other Methods (External beam, channelling, IBIC)

Particle Induced X-ray Emission



- Analogous to **EDX** using MeV protons or He
- No primary electron **Bremsstrahlung**, so low detection limits (1-10ppm)
- **Quantitative** (with RBS)
- Imaging resolution determined by **beam size** (*not* beam energy as in EDX)
- Very high cross-sections, so information is from **femtograms** of material



Johansson and Campbell, *PIXE*, Wiley 1995

PIXE

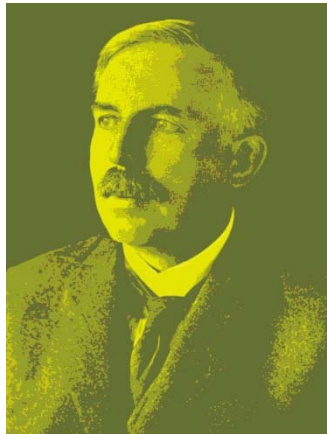
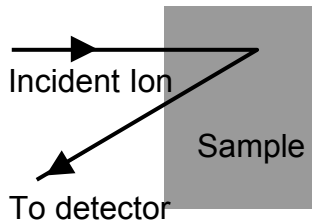
- **Sensitivity**
- **Scattering**
- **Backscattered particles**

SEM-EDS and PIXE spectra for a bulk bronze sample

- Atomic excitation
 - **PIXE (particle-induced X-ray emission)**
 - As for SEM-EDX or EPMA (electron excitation), or XRF (X-ray excitation)
 - High cross-sections relative to nuclear excitation
- Nuclear excitation
 - **Particle elastic scattering (RBS, EBS, ERD)**
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Rutherford BackScattering

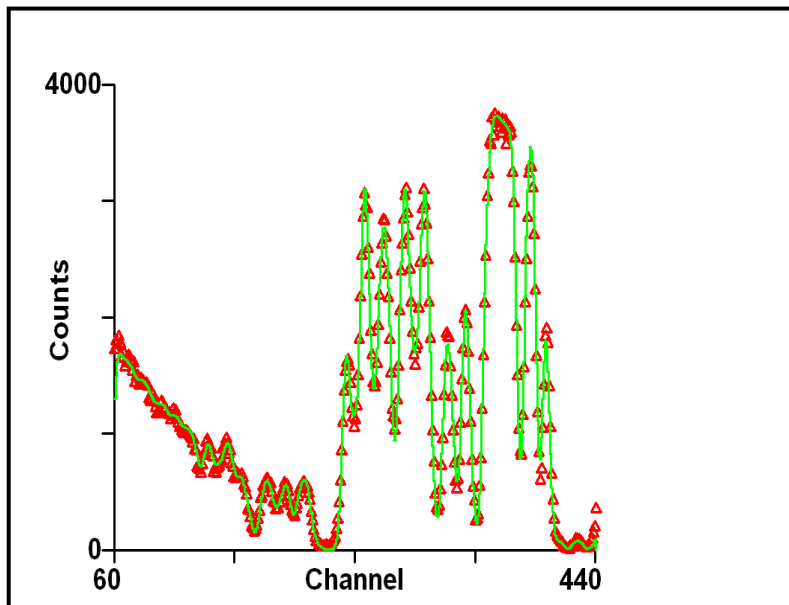
RBS



- Energy of ions scattering from nuclear collisions depends on **mass** and **depth**
- Detection limit around 0.1%
- **Depth profiling** with depth resolution <20nm
- **Analytical** cross-section σ (Coulomb potential)
- **Single** scattering (cf electron backscatters in SEM)

σ proportional to Z^2/E^2

- **Coulomb** potential (accurate)
- **Perfect** fitting of complex structures (inverse problem solved)

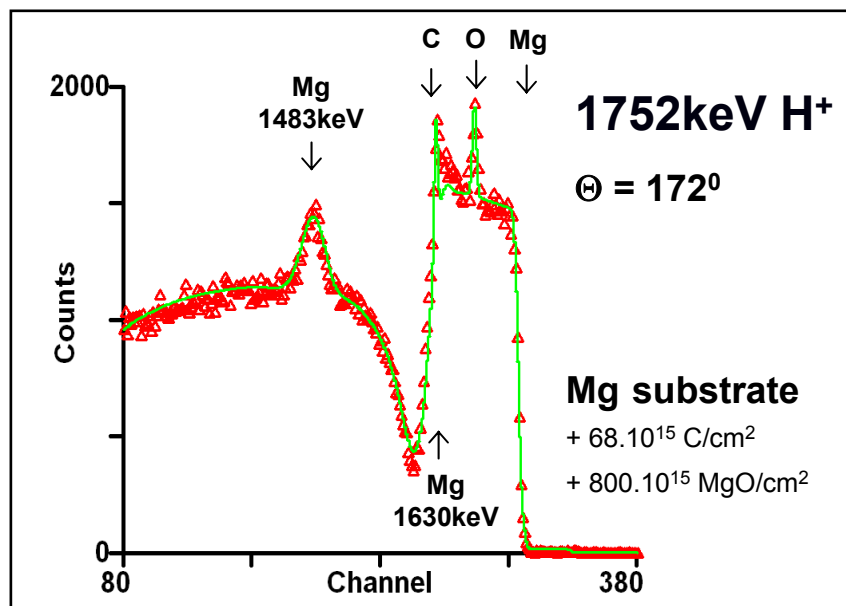


*Spectrum of zirconia/silica
multilayer optical coating (red),
with DataFurnace fit (green)*

C.Jeynes++ Surface & Interface Analysis 30 (2000) 237-242

Elastic (non-Rutherford) BackScattering

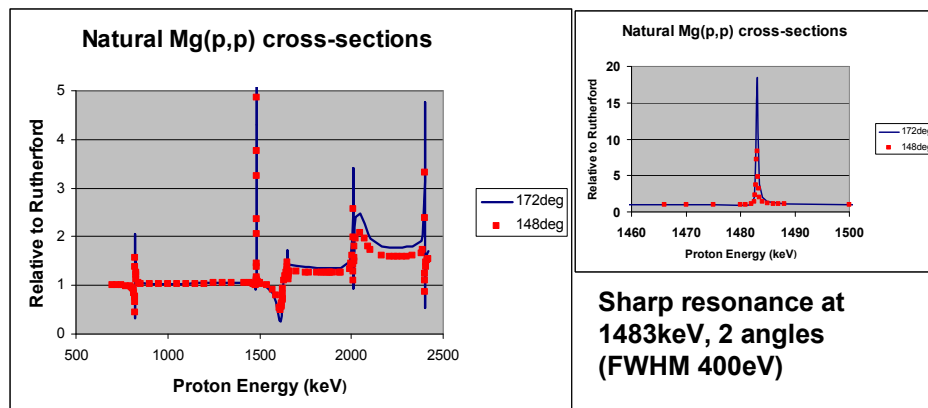
EBS



Benchmark experiment for evaluated Mg cross-sections

Gurbich & Jeynes, Nucl.Instrum.Methods **B265** (2007) 447-452

- Kinematics the same as for RBS
 - Scattering cross-sections not Coulomb
 - Can be fitted by solving Schrödinger's equation
 - See **SigmaCalc** at www-nds.iaea.org/iband/
- Gurbich, NIM B268 (2010) 1703**
- *Greatly enhanced* cross-sections often available for light elements
 - Cross-sections vary strongly with scattering angle

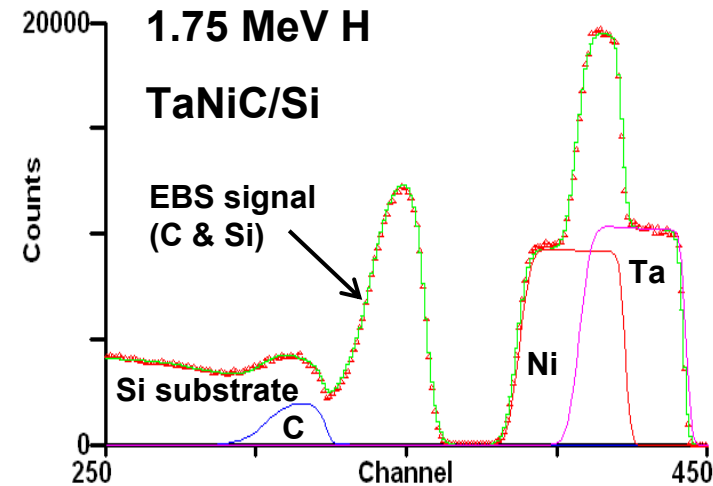


SigmaCalc scattering cross-sections for natural Mg (the isotopes behave differently) at two different scattering angles

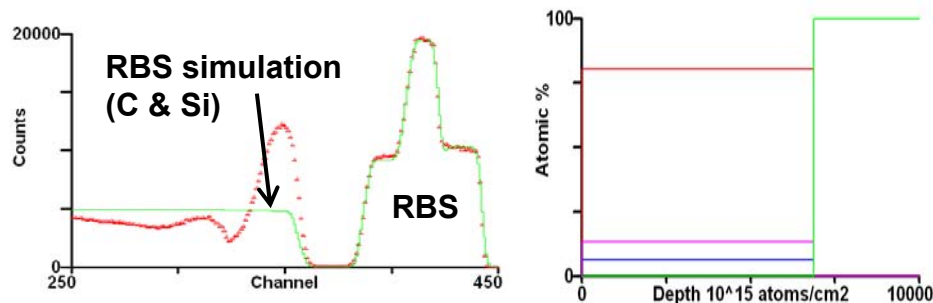
For sharp resonances one must correctly calculate energy straggling in depth (this effect can be LARGE)

Barradas et al, NIM **B247 (2006) 381**

Elastic (non-Rutherford) BackScattering



- Cross-sections not analytical and must be measured
- Light elements in heavy matrix can be measured (in this case 6.6at%C in TaNiC on a silicon background signal)
- Very large cross-section enhancements, depending on target atom and beam energy



*EBS spectrum of 750nm
TaNiC sputtered film on
Si substrate*

*The Ta & Ni signals are
Rutherford, but the C &
Si signals are strongly
non-Rutherford.*

Above: data & fit with Ta, Ni, C partial spectra shown

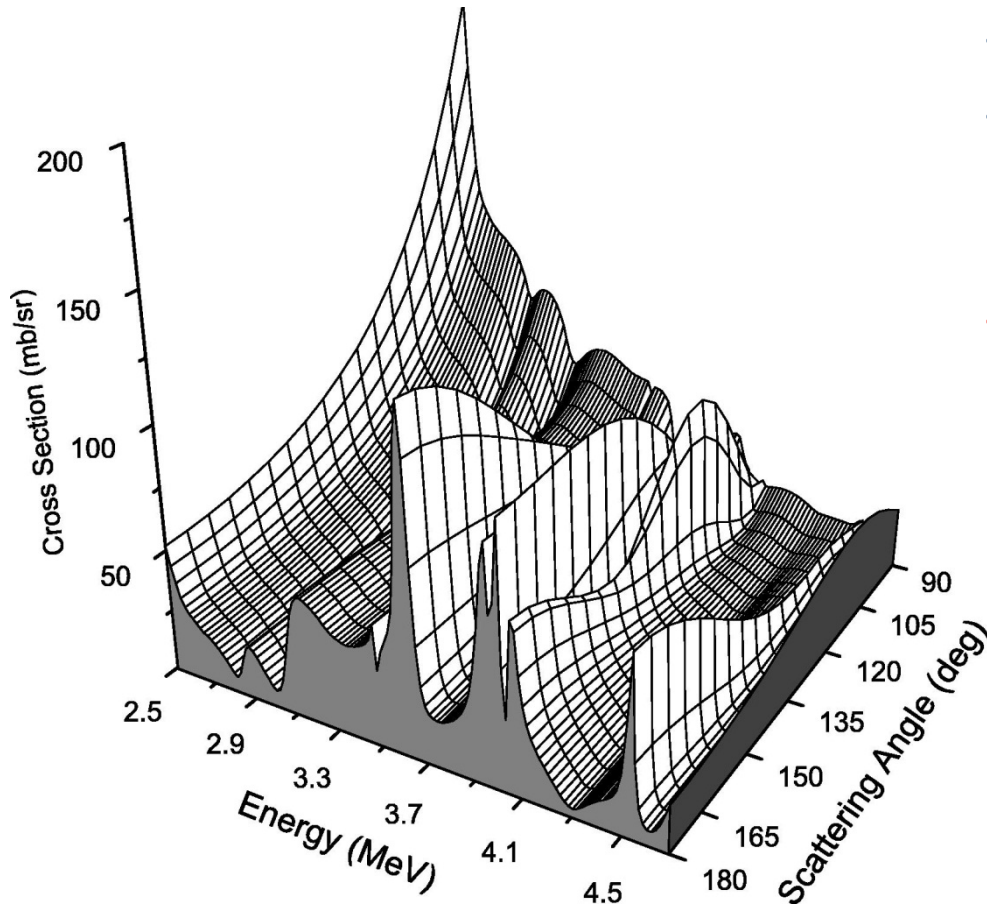
Below: simulation with RBS for Si & C

Right: Depth profile obtained

Jeynes *et al*, NIM B161-163 (2000) 287

EBS

Elastic (non-Rutherford) BackScattering



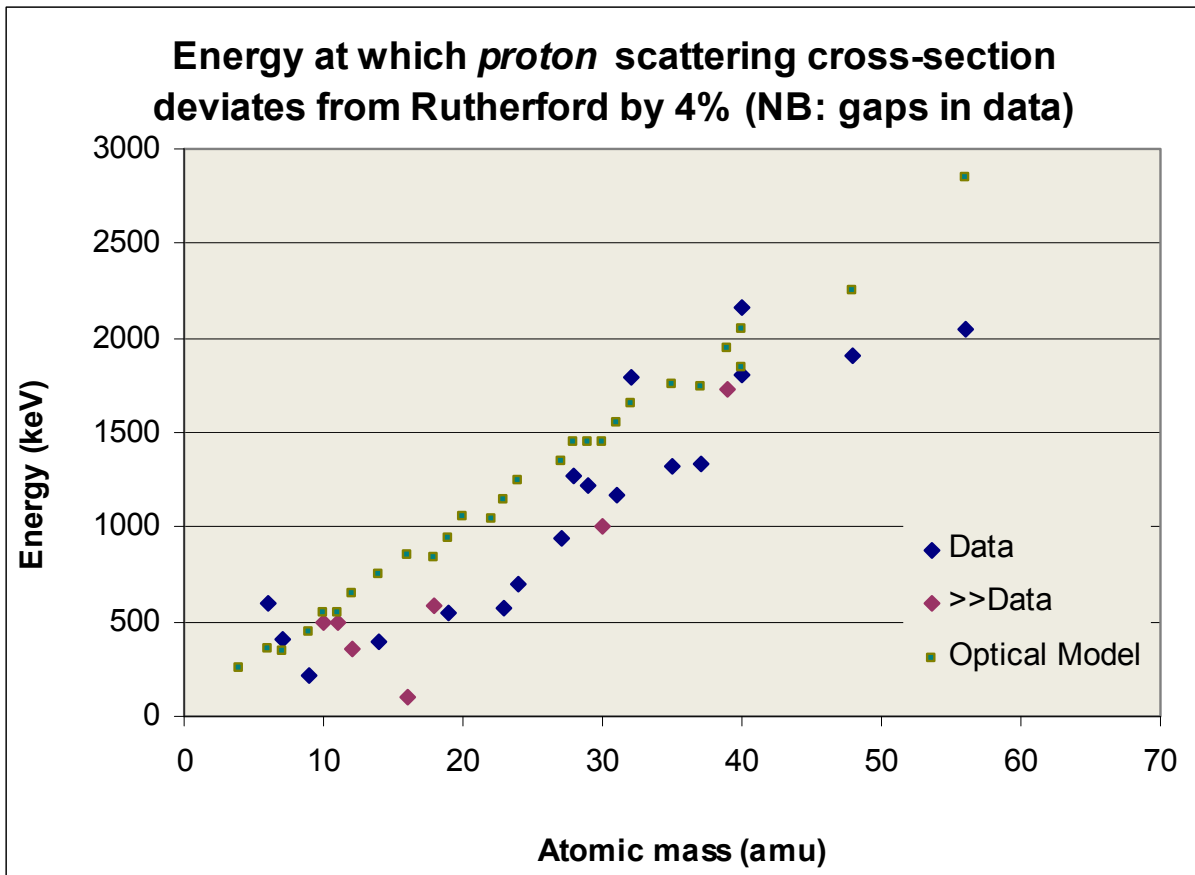
- $^{14}\text{N}(\alpha, \alpha)^{14}\text{N}$
- Variation of scattering cross-section function with scattering angle
- **Evaluated** by fitting nuclear data (including measured scattering cross-sections and gamma spectroscopy etc)

A.F.Gurbich et al, *Nucl. Instrum. Methods B*, 269 (2011) 40

See SigmaCalc at www-nds.iaea.org/iband1

EBS

Elastic (non-Rutherford) BackScattering



NB:

For 2 MeV protons cross-sections are **EBS** right up to Fe!

Notes:

“>>Data” (red): data not available for these nuclei, but boundary known to be (much) lower than point shown.

“Optical Model”: semi-classical quantum mechanics calculation

From Table 1 in Jeynes, Webb & Lohstroh, *Reviews of Accelerator Science and Technology*, 4 (2011) 41–82

EBS

Elastic Recoil Detection

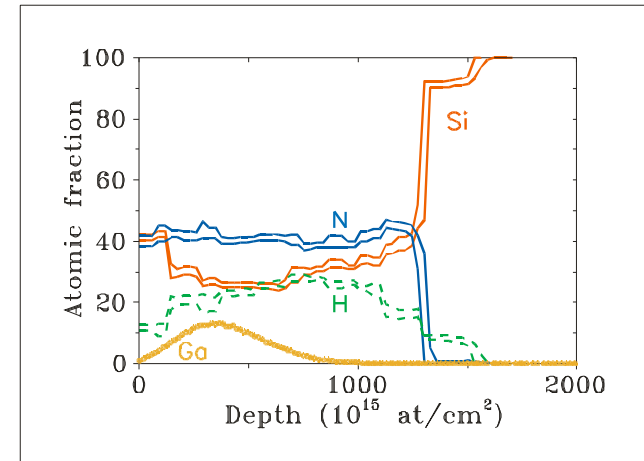
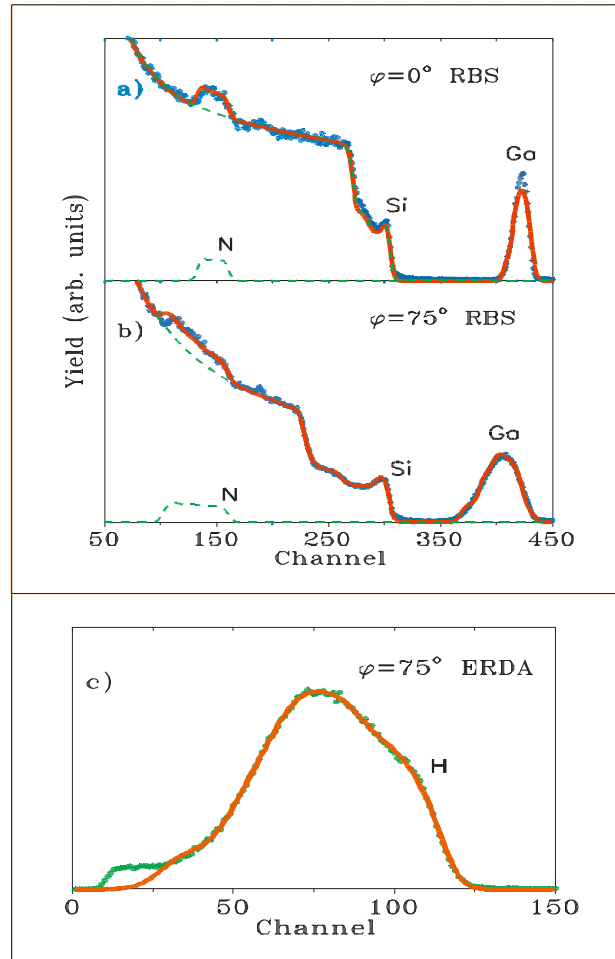
1.5MeV ^4He RBS

Normal incidence

Glancing incidence

Simultaneous with:
ERD

ERD



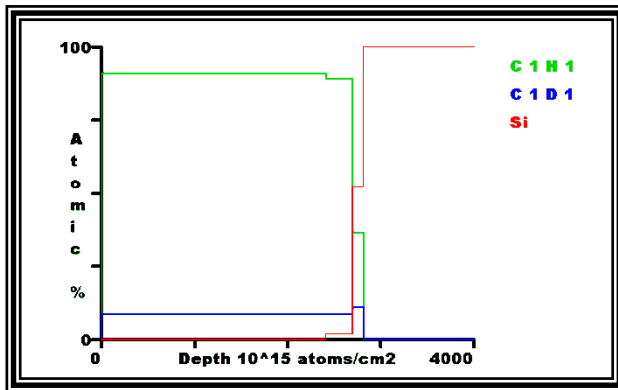
$\text{SiN}_x\text{:H}$ on Si

Ga implant to form a- GaN_x ?

Barradas *et al*, NIM B148, 1999, 463

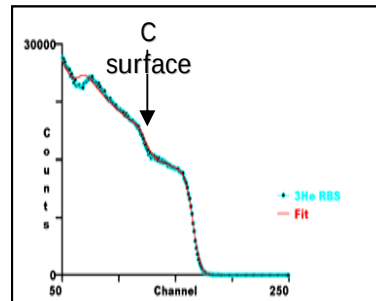
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Nuclear Reaction Analysis



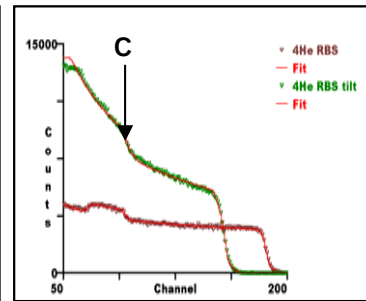
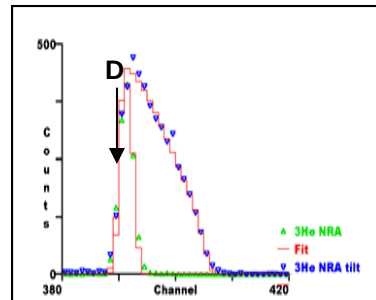
Depth profiling of 300nm CH:DH film on Si
using simultaneous RBS/NRA/ERD
and automatic spectrum inversion with
DataFurnace software (Jeynes et al J.Phys.D 36, 2003, R97)

0.7MeV ^3He RBS
Normal

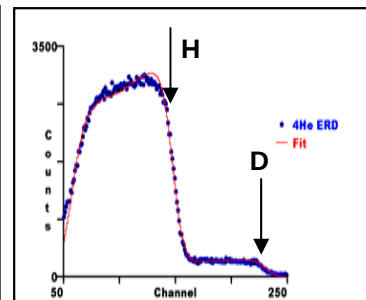


0.7MeV ^3He NRA
 $d(^3\text{He},p)^4\text{He}$
 $Q=18.35\text{MeV}$

Normal & glancing



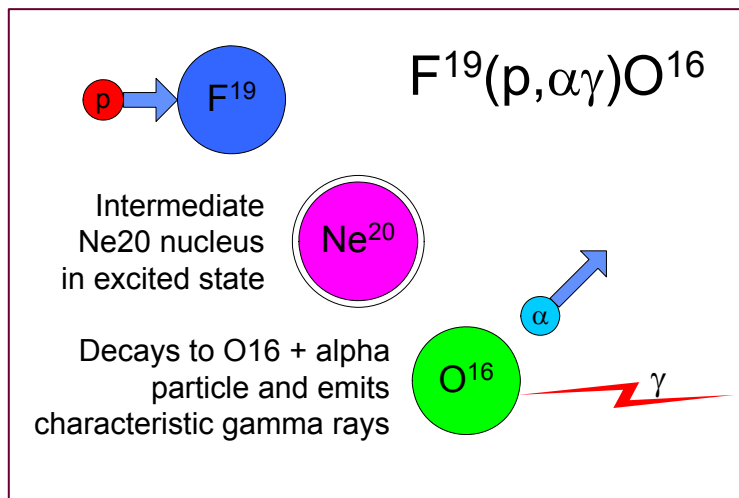
1.5MeV ^4He RBS
Normal & glancing



1.5MeV ^4He ERD
Glancing

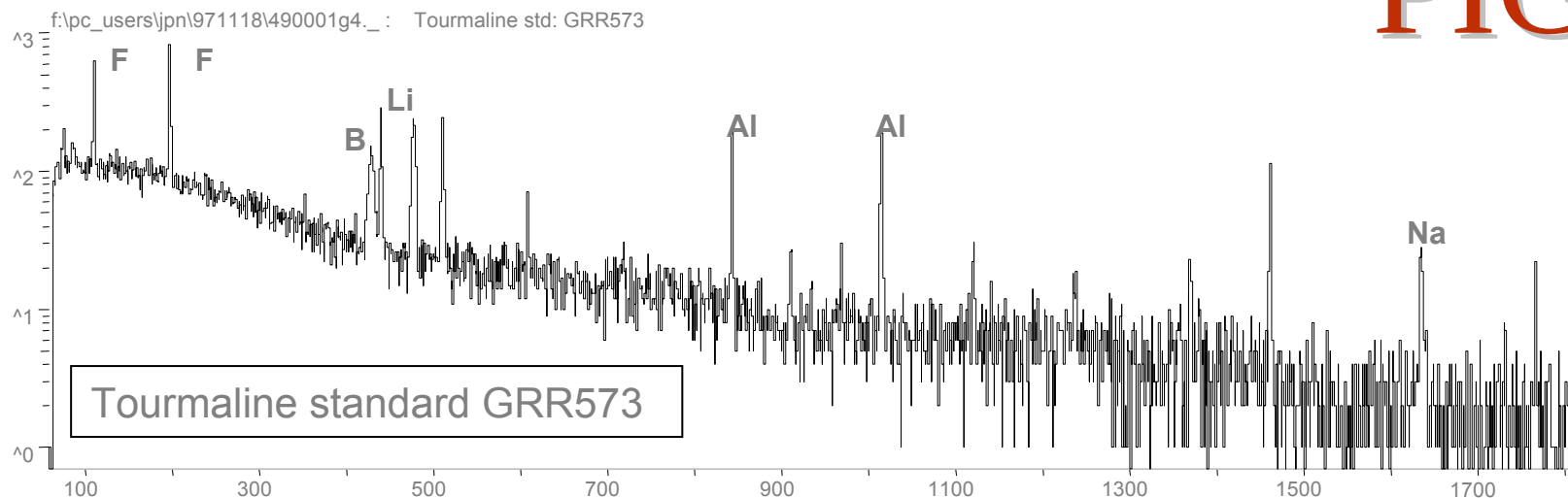
NRA

Proton Induced Gamma Ray Emission

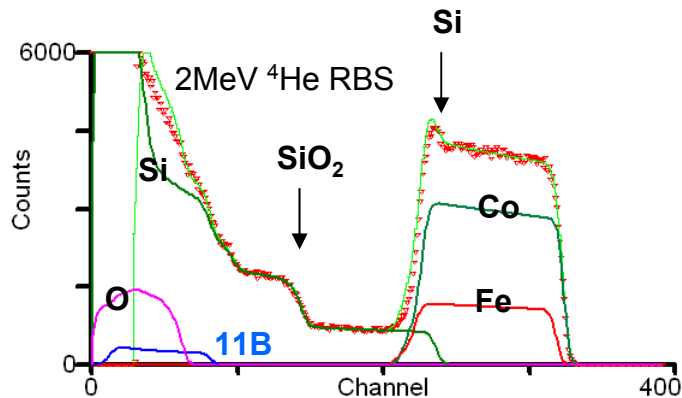


- MeV protons can overcome the Coulomb barrier of light nuclei to induce gamma emitting nuclear reactions
- Gamma energy is characteristic of specific isotopes
- Detection limits ~ 0.1 at%
- Useful for specific problems (e.g. ¹⁹F, ¹¹B, ²³Na, ²⁴Mg, ²⁷Al)
- *Special case of NRA*

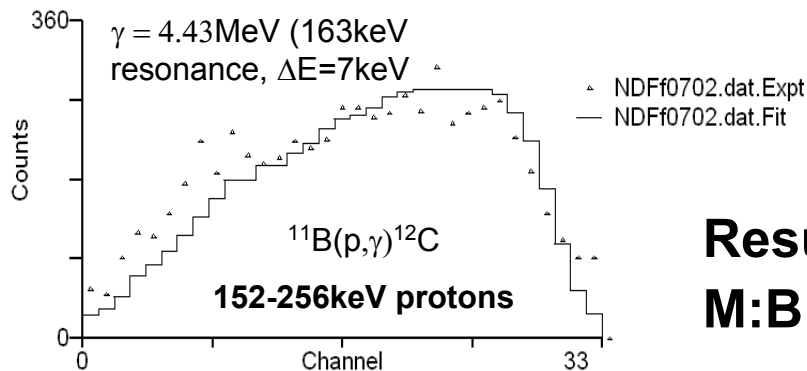
PIGE



NRP (PIGE) of metal boro-silicide sample



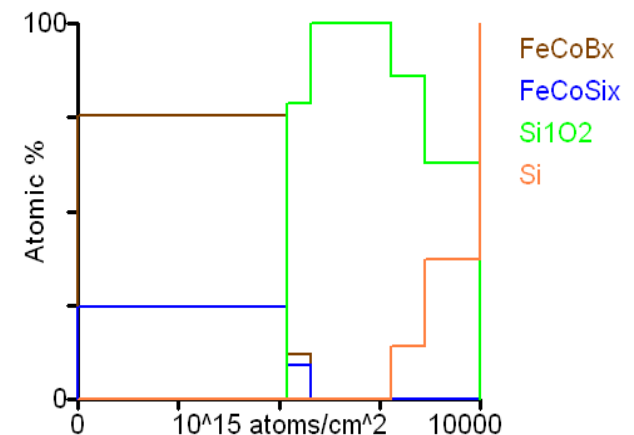
- Sample structure from **RBS** (boron content poorly determined)
- **Co/Fe=3.8** from 2.2MeV **PIXE**
- **Direct PIGE signal for B with a proton beam scanned 0.1-0.3 MeV**



Result is:
M:B:Si = 26:58:16

DataFurnace integrates RBS/PIXE/PIGE for self-consistent analysis

Barradas et al, Nucl. Instrum. Methods B, 268 (2010) 1829–1832



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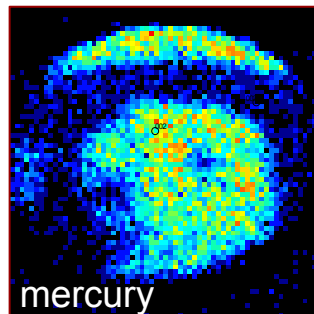
External Beam

- 100 Reichmark bank note from Germany dated 1920
- Can we analyse the inks?

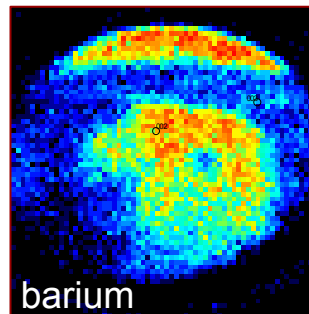


scanned
area

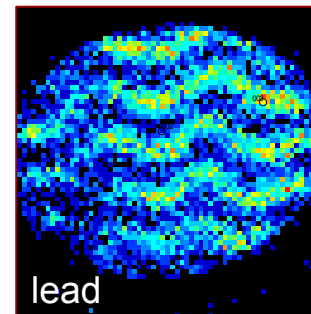
Selection of PIXE
elemental maps
(3x3 mm)



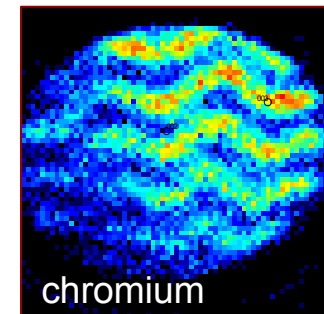
mercury



barium



lead



chromium

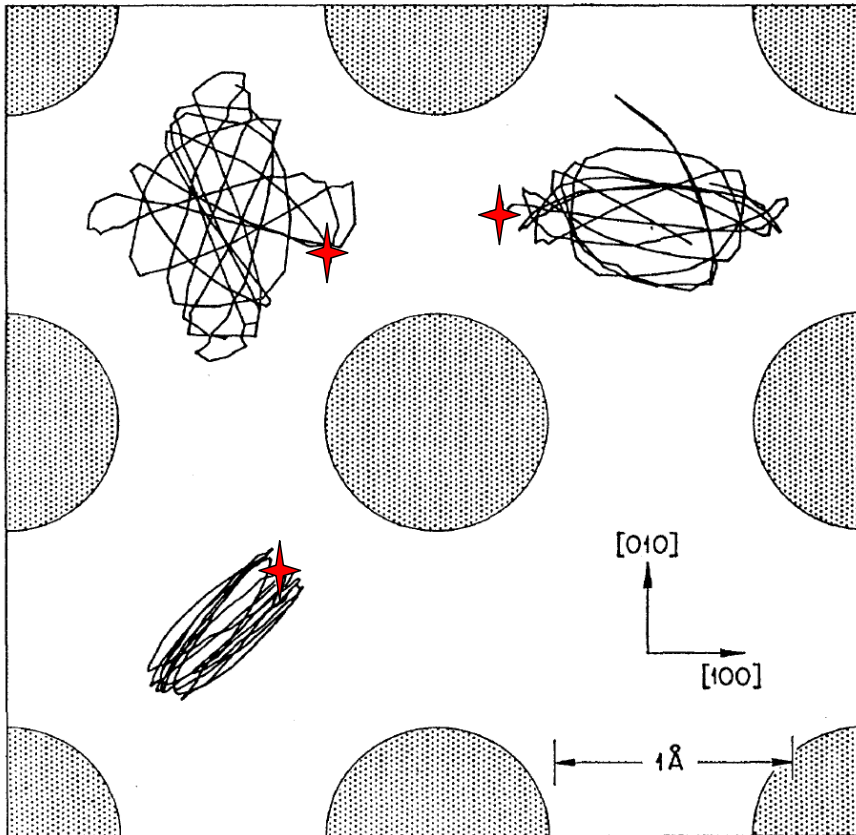
Red ink (head of eagle)

Green ink (wavy lines)

10 other elements detected

Analysis carried out in 10 minutes with no visible marking of the paper

Channelling



Projection of three calculated trajectories of **1 keV Cu** incident (at points marked with stars) along the (001) direction of a face centred cubic Cu crystal. The trajectories for **250 collisions** are shown and the truncated Bohr potential is used.

Range in channelling can be up to **25 times** “random” range

Robinson & Oen, *Phys. Rev*, 132 (1963) 2385

Channelling – crystalline damage example

c-Si

Channelling normal
1.2 MeV $^4\text{He}^+$
40 μm spot

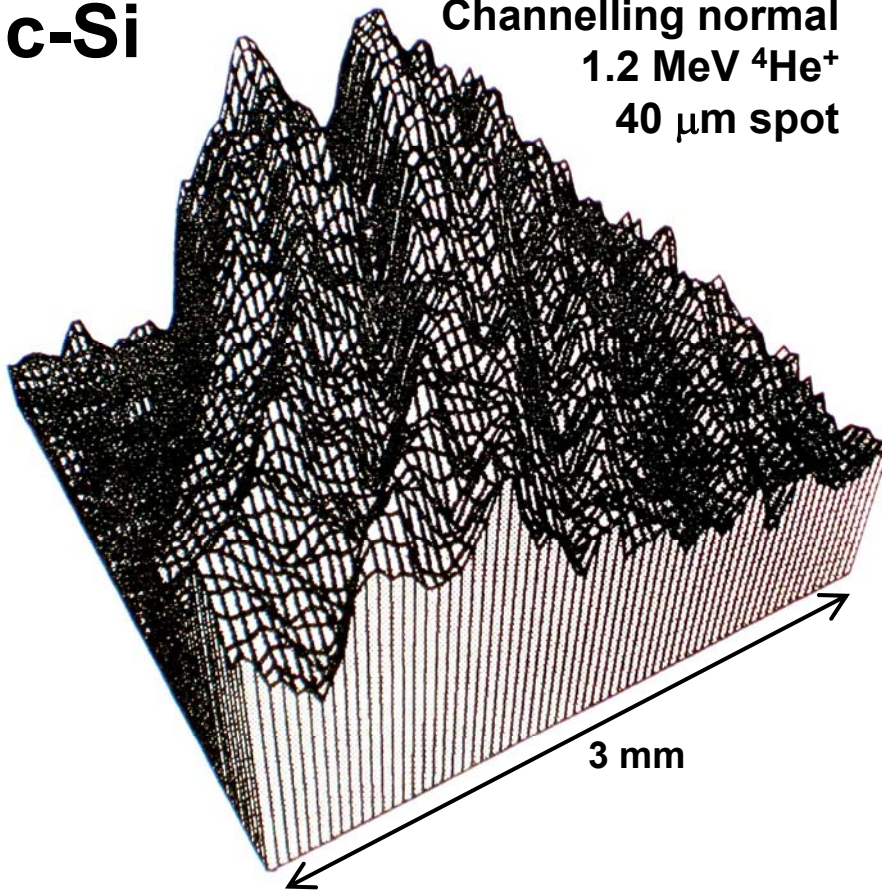


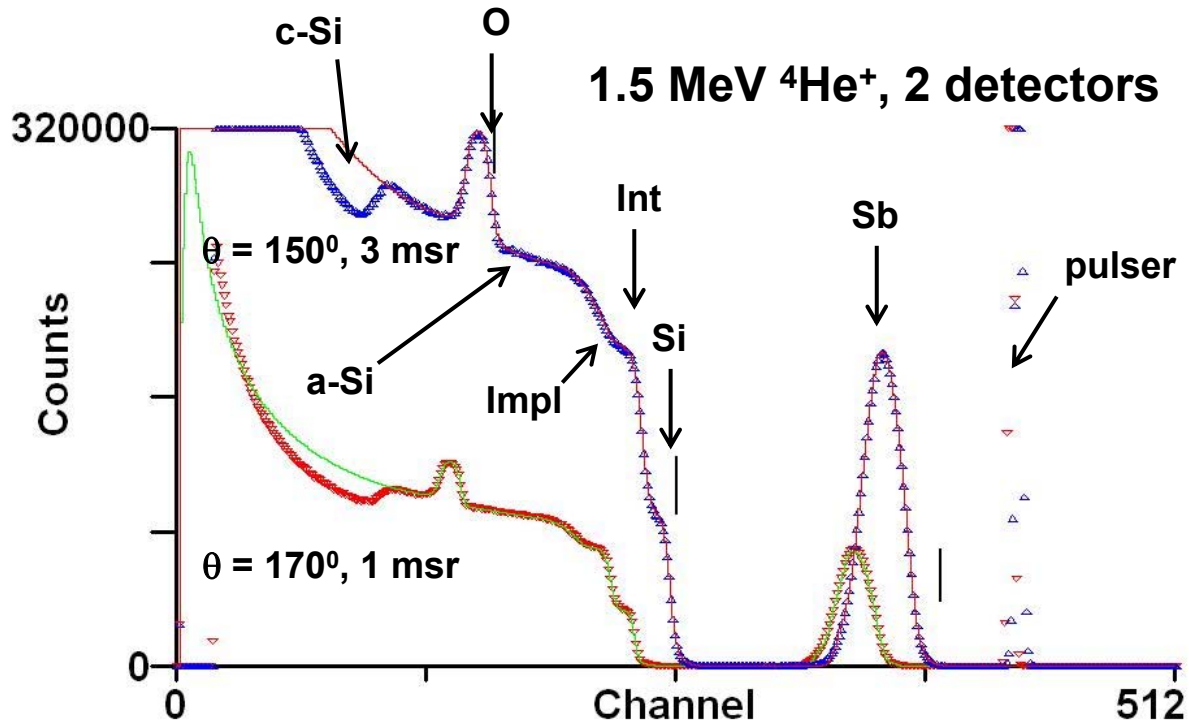
Image of circular damage tracks in a silicon sample turned on an ultra-stiff lathe with a **single-point diamond** tool.

Signal is the low-energy part of the RBS Si signal: high yield means high damage. 128×128 pixels, pixel area (23.4 μm)², 0.15 nC/pixel.

This is **plastic** deformation of a **brittle** material, with an a-Si layer up to **350 nm** thick over a **dislocation array** $\sim 5 \cdot 10^{10}/\text{cm}^2$.

Jeynes, Puttick, Gärtner *et al*,
Nucl. Instrum. Methods B, 118 (1996) 431

Channelling



481.10^{14} Sb/cm² certified standard implant
Amorphised to 630 nm, 90 nm surface oxide

Barradas et al, Nucl. Instrum. Meth. B, 266 (2008) 1198-1202

The He beam is normal to the sample, channelled in the (100) direction.

The Si and O edges are marked.

The pulser and the Sb implant peaks are marked

The SiO₂/Si interface signal is marked "Int"

The energy loss in the Sb gives a dip in the Si signal, marked "Impl"

The interface between the a-Si and c-Si is clear.

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Towards truly simultaneous PIXE and RBS analysis of layered objects in cultural heritage

C. Pascual-Izarra (**Madrid**), N. P. Barradas, M. A. Reis (**Lisbon**),
C. Jeynes (**Surrey**), M. Menu, B. Lavdrine, J. J. Ezrati, S. Röhrs (**Louvre**)

Nucl. Instrum. Methods B261, 426-429 (2007)

3 MeV H PIXE

3 MeV H EBS

3 MeV He RBS

Fitted depth
profile

Niepce's first Heliography:
Paysage à Saint-Loup de Varennes (1827)

**Corrosion products demonstrated
by PIXE/RBS/EBS to be tin oxide in
a tin/lead matrix**

Characterization of paint layers by simultaneous self-consistent fitting of RBS/PIXE spectra using simulated annealing

L. Beck (**Louvre**), C. Jeynes (**Surrey**), N.P.Barradas (**Lisbon**)

Nucl. Instrum. Methods **B266**, 1871-1874 (2008)

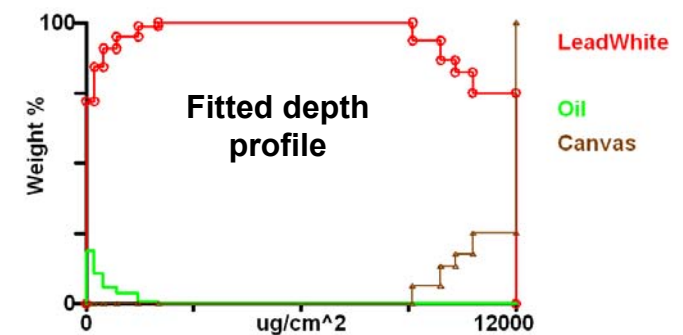
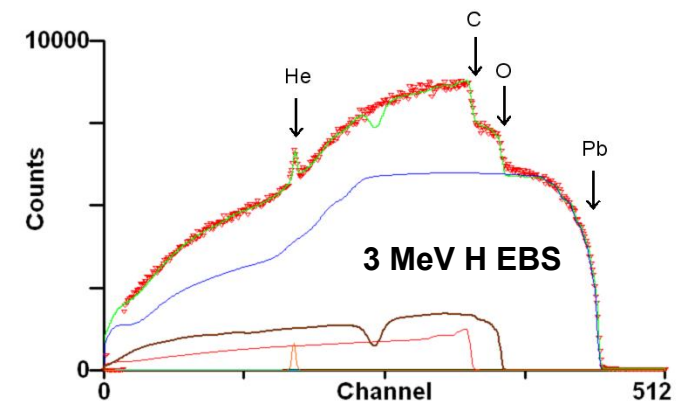


"La Bohémienne", Frans Hals 1630

AGLAE : Accélérateur Grand
Louvre d'Analyse Élémentaire

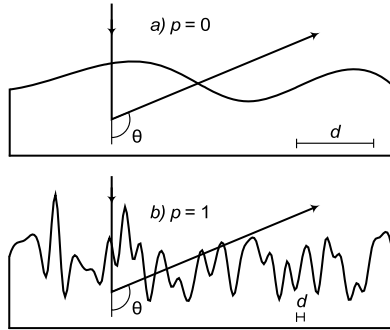


Ochre (haematite)
pigment located
and quantified by
PIXE/RBS/EBS



Roughness

Molodtsov, Gurbich & Jeynes, J.Phys. D: Appl. Phys. 41, 205303 (2008) (7pp)

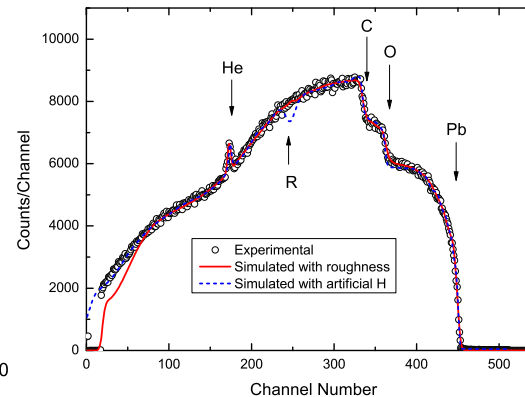
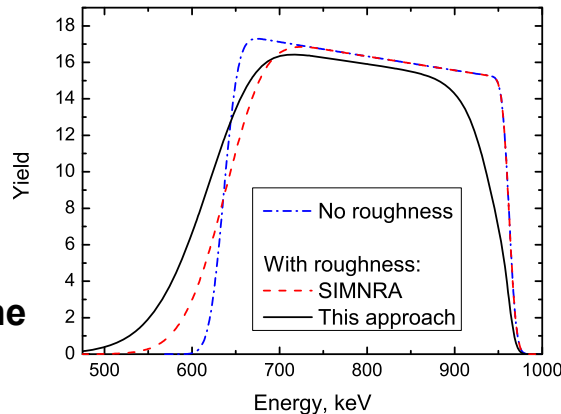


- Beam re-entering through surface asperities gives **extra surface energy loss** due to extra pathlength x
- Generate a general rough surface giving a **pathlength density function $f(x)$**
- Characterise roughness with **TWO PARAMETERS**:
“sharpness” σ and “scale” p
- Parameterise $f(x)$ explicitly using extensive **Monte Carlo** calculations

$$f(x) = (1-n)\delta(x) + n \frac{b^{a+1}}{\Gamma(a+1)} x^a \exp(-bx)$$

SIMNRA (and NDF)
can simulate only
some of the
roughness effect

New algorithm
calculates the high
energy effect and the
lower max yield



New algorithm
correctly calculates
the smearing of the
EBS resonances “R”.

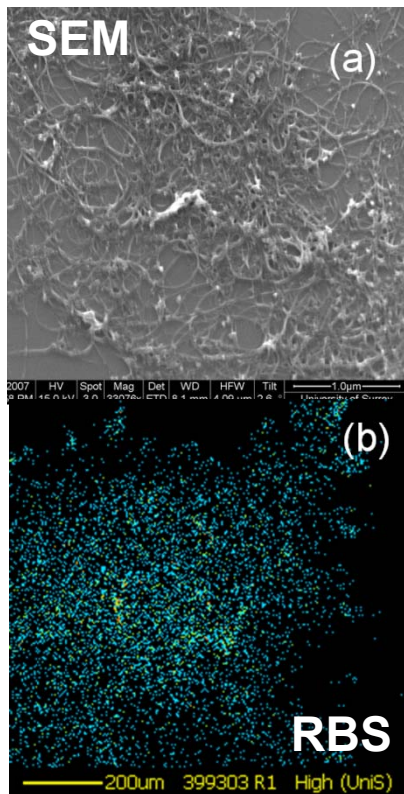
**The effect on the
depth profiles is
LARGE**

- Most real samples are **ROUGH!**
- Extract scale and sharpness from BS spectra **without MonteCarlo**
- Valid for **RBS, EBS, ERD, PIXE, NRA**
- **Correct depth profiles!**

RBS/EBS/PIXE measurement of single-walled carbon nanotube modification by nitric acid purification treatment

J.C.G. Jeynes, C. Jeynes, K.J. Kirkby, M. Rummeli, S.R.P. Silva

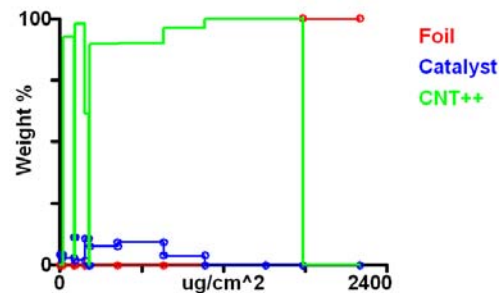
Nucl. Instrum. Methods **B266**, 1569-1573 (2008)



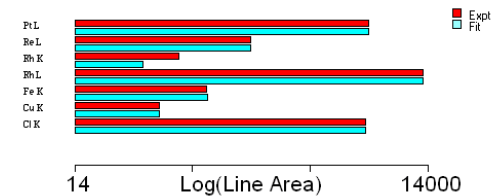
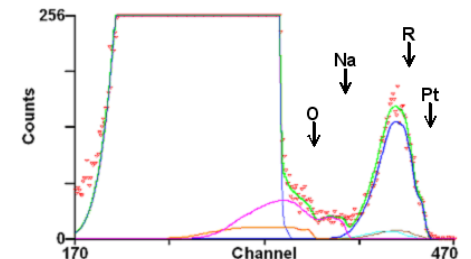
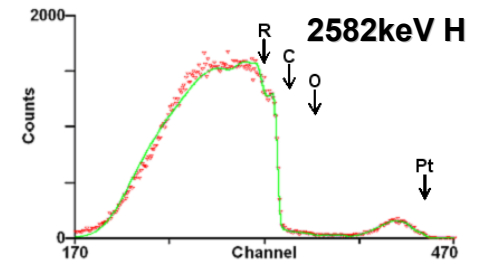
SWCNT on mylar

O quantified by PIXE/RBS/EBS in the presence of mixed heavy metal **catalyst** content of CNT with heavy roughness

Catalyst contains Pt, Rh, Re, Fe, Cu, Cl, Na. Roughness effects marked "R"



Fitted depth profile

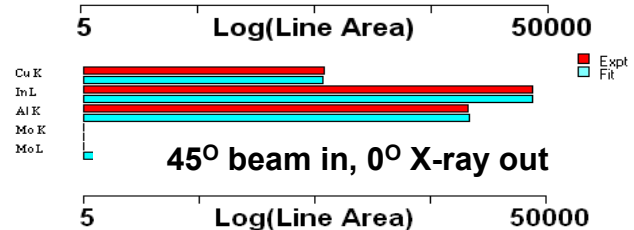
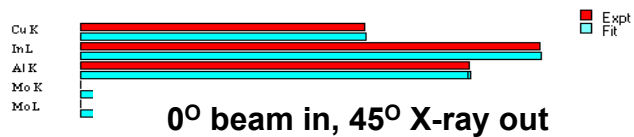
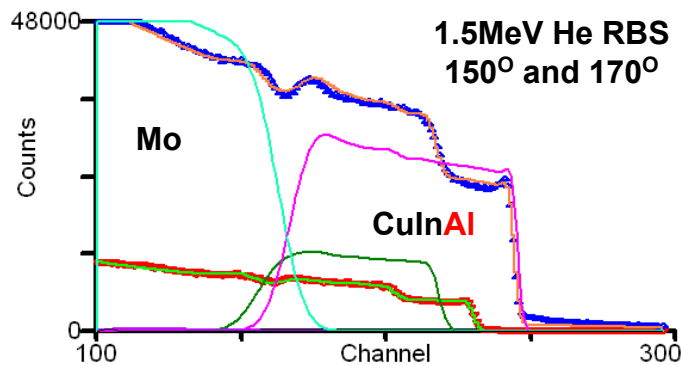


RBS/EBS & PIXE data & fits

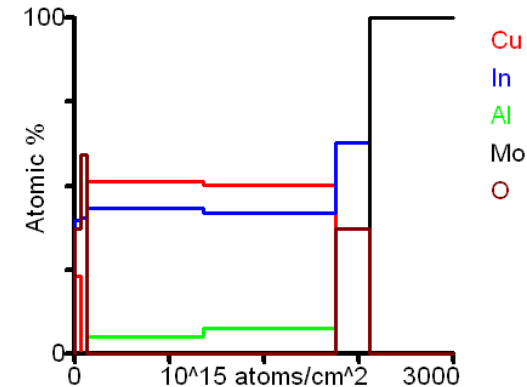
Characterisation of thin film chalcogenide PV materials using MeV ion beam analysis

Chris Jeynes, G.Zoppi, I.Forbes, M.J.Bailey, N.Peng

IEEE Proceedings of Supergen Conference, Nanjing,
 April 2009, DOI:10.1109/SUPERGEN.2009.5348162

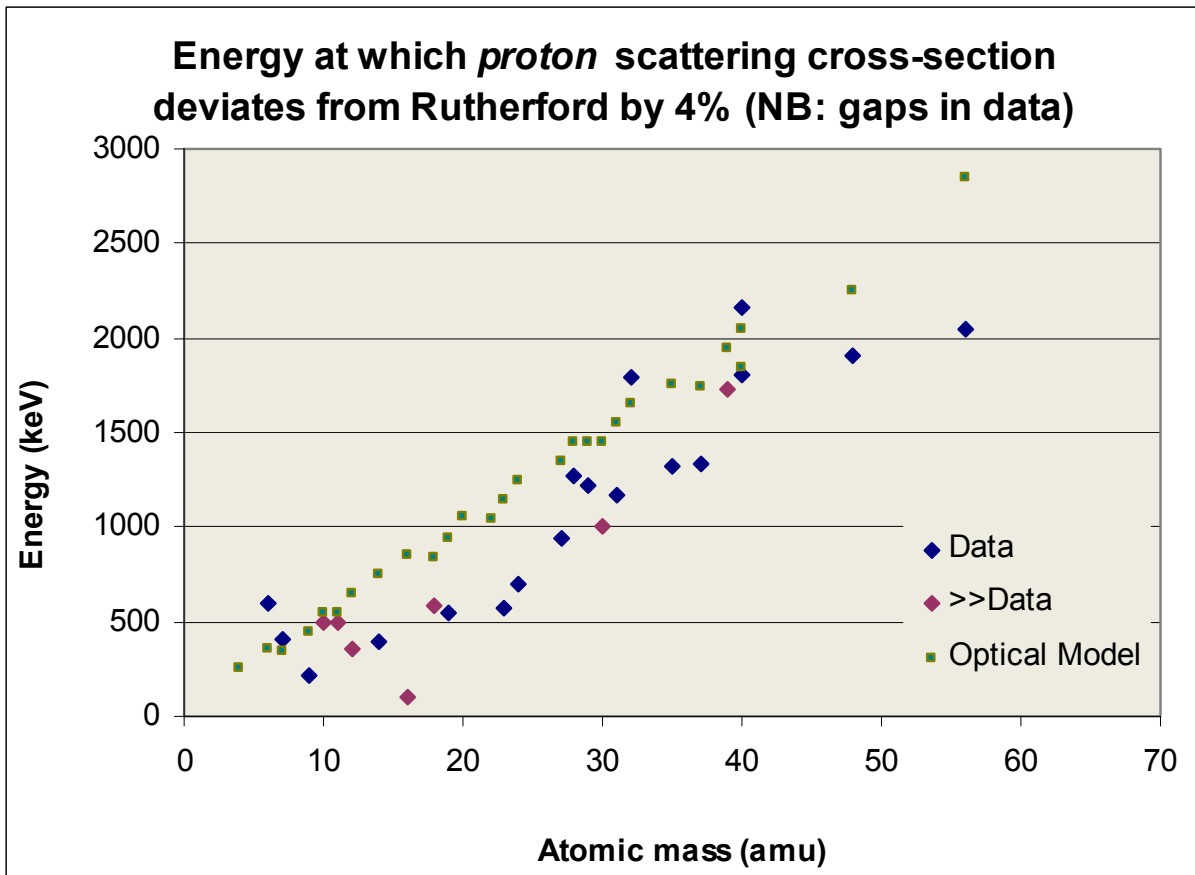


He-PIXE simulated by
equivalent-velocity H-PIXE



- CIAS semiconductor on Mo electrode
- Precursor material (not selenided yet)
- Al **invisible** in backscattering
- Strong layering: PIXE **uninterpretable** without profile independently available
- **Differential PIXE** to profile Al
- Essential to fit roughness (**non-uniform thickness**) to reproduce RBS spectra
- Good fit **essential** for reliable profile

Elastic (non-Rutherford) BackScattering



NB:

For 2 MeV protons cross-sections are **EBS** right up to Fe!

Notes:

“>>Data” (red): data not available for these nuclei, but boundary known to be (much) lower than point shown.

“Optical Model”: semi-classical quantum mechanics calculation

From Table 1 in Jeynes, Webb & Lohstroh, *Reviews of Accelerator Science and Technology*, 4 (2011) 41–82

EBS

Information in BS spectra with few counts

N.P.Barradas, C. Jeynes, M. Jenkin, P.K. Marriott

Thin Solid Films 343-344 (1999) 31-34

1.5 MeV He RBS

- PIXE cross-sections $\gg$ RBS
- 100 pA common for PIXE
- Poor statistics in particle spectra!

This **Bayesian analysis** demonstrates that even spectra with very small collected charge have lots of information!

Don't throw away good data!
Always do BS with PIXE!
Always do PIXE with BS!

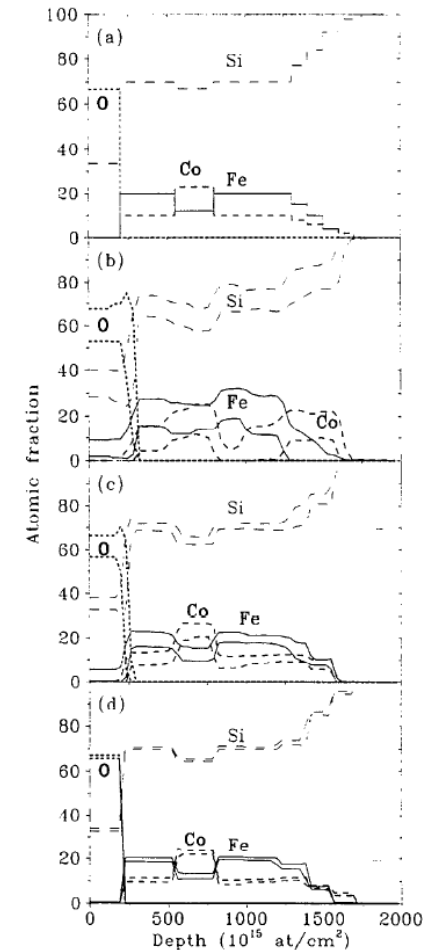


Fig. 1. (a) Theoretical depth profile used to generate the test RBS spectra analysed, with (b) high, (c) medium, and (d) low level of noise. Confidence limits (± 1 standard deviation) of the posterior probability distribution obtained with MCMC for the different elements. Oxygen was only allowed to exist at the surface of the sample, and Co and Fe were restricted to depths below 2×10^{15} at/cm².

Contents

- Introduction – Materials Analysis
 - ***Surrey Ion Beam Centre***
 - Materials Modification by Ion Implantation
 - Thin Film Depth Profiling by Ion Beam Analysis
 - ***Ion Beam Analysis Overview***
 - Atomic Excitation – PIXE
 - Nuclear Excitation – RBS, EBS, ERD, NRA
 - Scanning microbeam, channelling, external beam
 - Accurate analysis!
 - ***PIXE + Backscattering – self-consistent analysis***
 - ***Accurate analysis!***
- The $^{28}\text{Si}(\alpha, \alpha)^{28}\text{Si}$ reaction
- Summary

First *critical* 1% accuracy RBS report, 2012

**analytical
chemistry**

[dx.doi.org/10.1021/ac300904c](https://doi.org/10.1021/ac300904c)

Article

pubs.acs.org/ac

Accurate Determination of Quantity of Material in Thin Films by Rutherford Backscattering Spectrometry

C. Jeynes,^{*,†} N. P. Barradas,[‡] and E. Szilágyi[§]

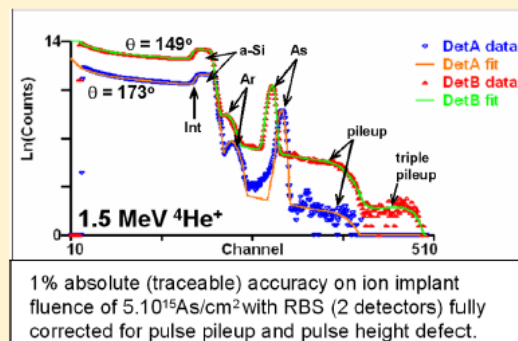
[†]University of Surrey Ion Beam Centre, Guildford, England

[‡]Instituto Superior Técnico/ITN, Universidade Técnica de Lisboa, Sacavém, Portugal

[§]Institute for Particle and Nuclear Physics, Wigner Research Centre for Physics, Budapest, Hungary

 Supporting Information

ABSTRACT: Ion beam analysis (IBA) is a cluster of techniques including Rutherford and non-Rutherford backscattering spectrometry and particle-induced X-ray emission (PIXE). Recently, the ability to treat multiple IBA techniques (including PIXE) self-consistently has been demonstrated. The utility of IBA for accurately depth profiling thin films is critically reviewed. As an important example of IBA, three laboratories have independently measured a silicon sample implanted with a fluence of nominally 5×10^{15} As/cm² at an unprecedented absolute accuracy. Using 1.5 MeV ⁴He⁺ Rutherford backscattering spectrometry (RBS), each lab has demonstrated a combined standard uncertainty around 1% (coverage factor $k = 1$) traceable to an Sb-implanted certified reference material through the silicon electronic stopping power. The uncertainty budget shows that this accuracy is dominated by the knowledge of the



C. Jeynes, N.P.Barradas, E. Szilágyi, *Analytical Chemistry*, 84(14) (2012) 6061-6069

Contents

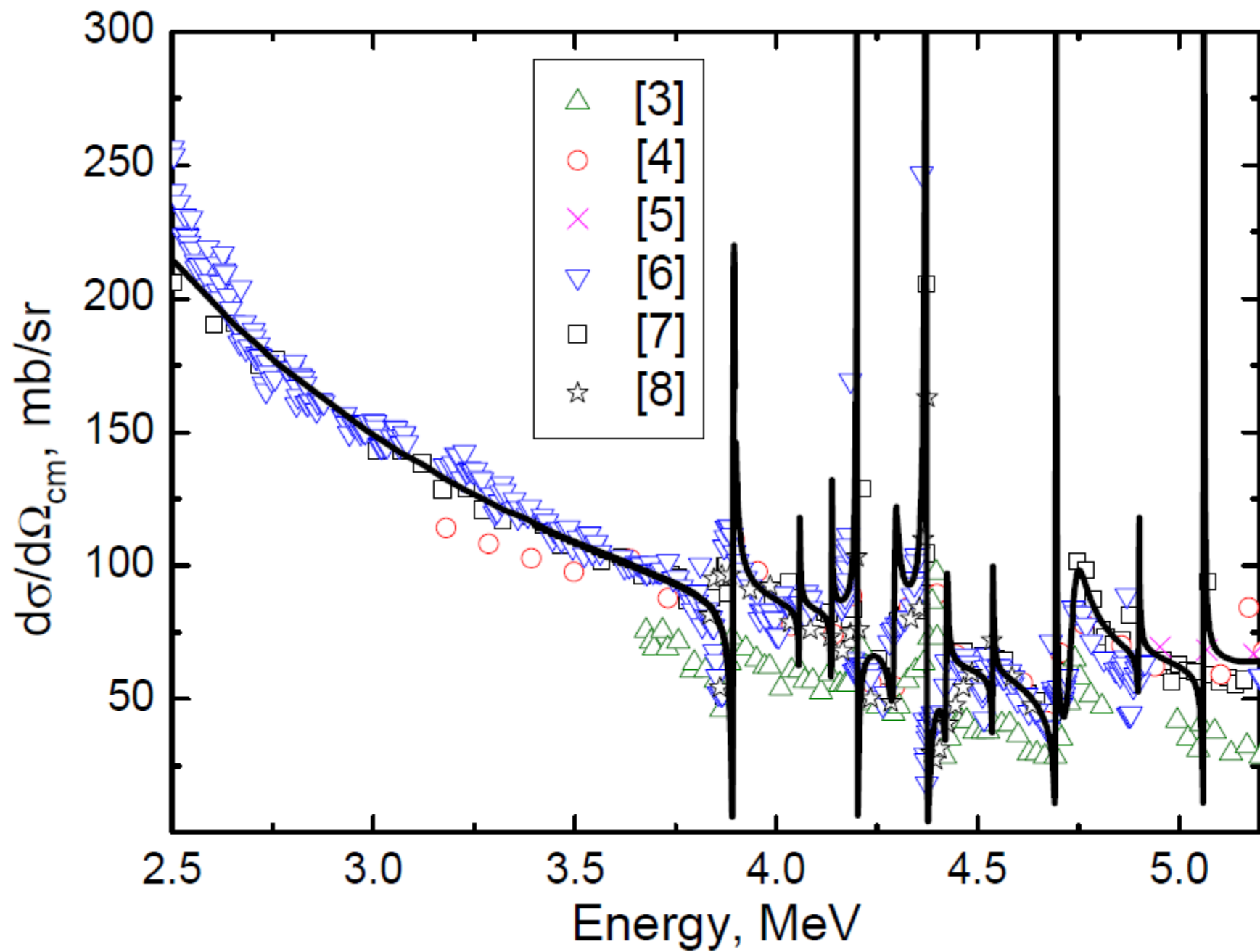
- Introduction – Materials Analysis
- The $^{28}\text{Si}(\alpha, \alpha)^{28}\text{Si}$ reaction
 - *Why?*
 - *Previous work*
 - *R-matrix modelling*
 - *Beam Energy*
 - *Benchmarking*
 - *Results*
- Summary

Why Silicon (α, α)?

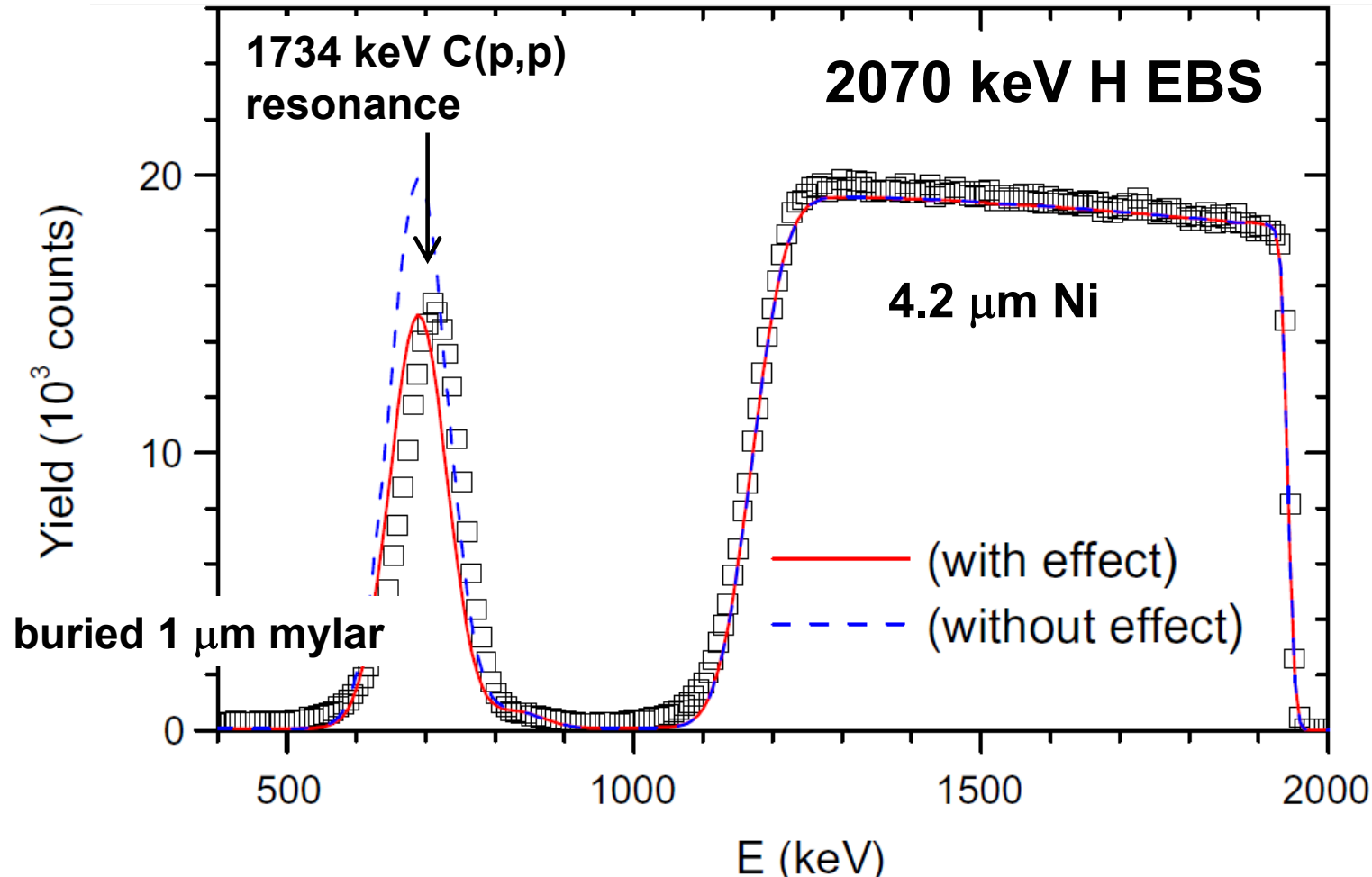
- Silicon
 - *Important semiconductor material*
 - *2nd most abundant element in the earth's crust*
- Si is the matrix for many samples of interest – without Si cross-sections we cannot use EBS!
 - *For example, the strong $^{12}\text{C}(\alpha, \alpha)^{12}\text{C}$ resonance at 4262 keV*
 - *For example, the strong $^{14}\text{N}(\alpha, \alpha)^{14}\text{N}$ resonance at 4475 keV*
 - *For example, thick samples need high energy*
- Si is important in the stellar nucleosynthesis α process
 - *^{28}Si is 8th and ^{32}S is 10th most abundant element in Universe*
 - *Elastic scattering cross-sections central to the nuclear model*
 - *Astrophysics interest*

Previous Work: $^{28}\text{Si}(\alpha,\alpha)^{28}\text{Si}$ measurements

- K.-M. Källman, *Zeitschrift für Physik A*, 356, 287 (1996); 3.6 – 5.8 MeV, 19 angles 173°-82°, thick film target; R-matrix analysis (reported in Nuclear Data Sheets 2011)
- A. Coban, F.Z. Khiari, M.S. Abdelmonem, A. Aksoy, A.A. Naqvi, *Nuclear Physics A* 678, 3 (2000); 130° to 170° with 10° step; 3.1 – 7.7 MeV
- J.J. Lawrie, A.A. Cowley, D.M. Whittal, S.J. Mills, W.R.McMurray, *Zeitschrift für Physik A*, 325, 175 (1986); 168°, 126°, 89°, 70°; 4.9 - 11.7 MeV
- M.K. Leung, Ph.D. dissertation, Univ. of Kentucky (1972); 165°, 2.5 - 6 MeV
- H.-S. Cheng, H. Shen, F. Yang, J.-Y. Tang, *Nuclear Instruments and Methods in Physics Research B* 85, 47 (1994); 170°, 2 – 9 MeV
- R. Somatri, J.F. Chailan, A.Chevarier, N.Chevarier et al., *Nucl. Instrum. Methods in Physics Research B* 113, 284 (1996); 172°, 3.8 – 4.6 MeV



Previous Work: spectral simulation code

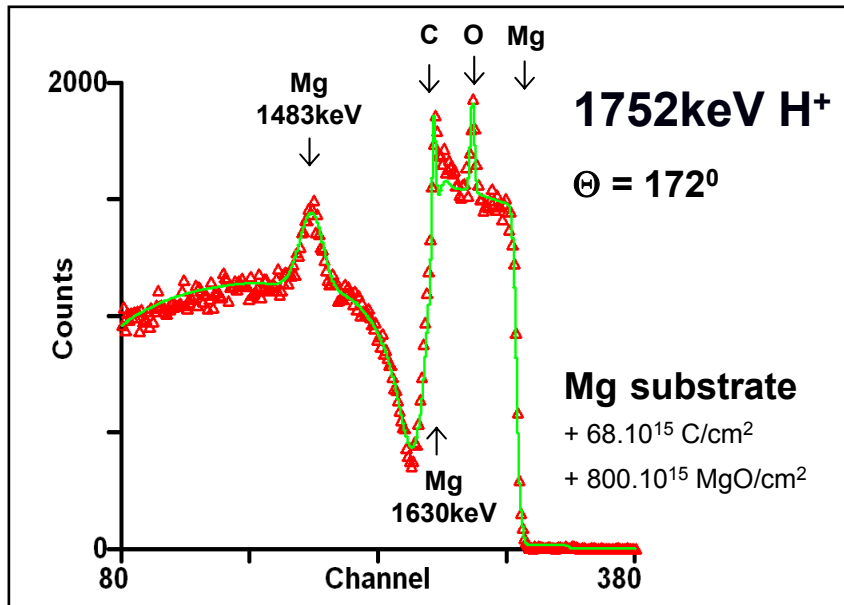


N.P.Barradas & C.Jeynes, Nucl. Instrum. Methods B, 266 (2008) 1875-1879

DataFurnace (NDFv.9) code to calculate **sharp resonances** correctly

Previous Work: spectral simulation code

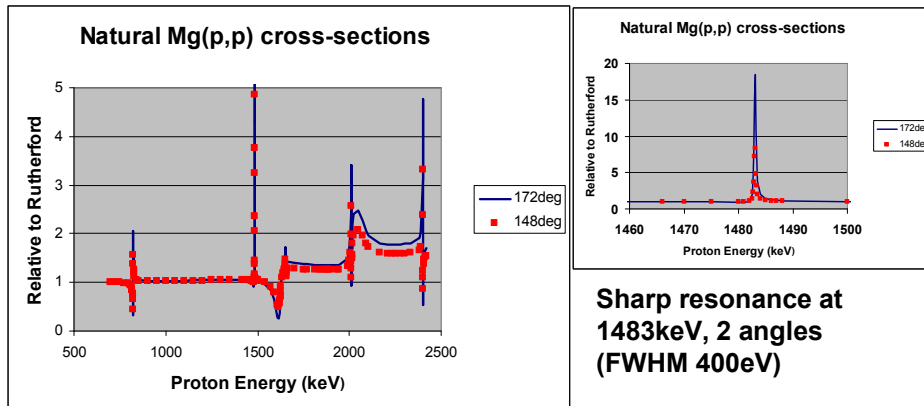
EBS



Benchmark experiment for evaluated Mg cross-sections

Gurbich & Jeynes, Nucl.Instrum.Methods **B265** (2007) 447-452

- Kinematics the same as for RBS
 - Scattering cross-sections not Coulomb
 - Can be fitted by solving Schrödinger's equation
 - See **SigmaCalc** at www-nds.iaea.org/iband/
- Gurbich, NIM B268 (2010) 1703**
- *Greatly enhanced* cross-sections often available for light elements
 - Cross-sections vary strongly with scattering angle



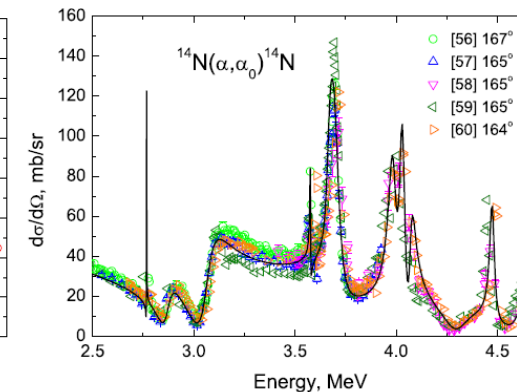
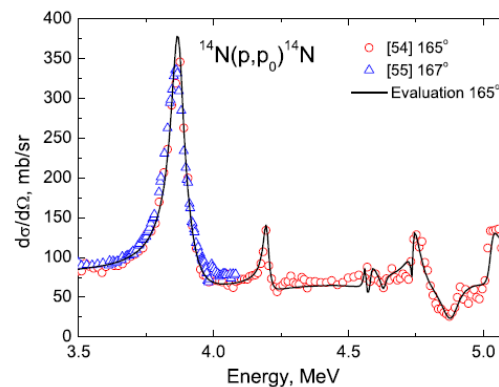
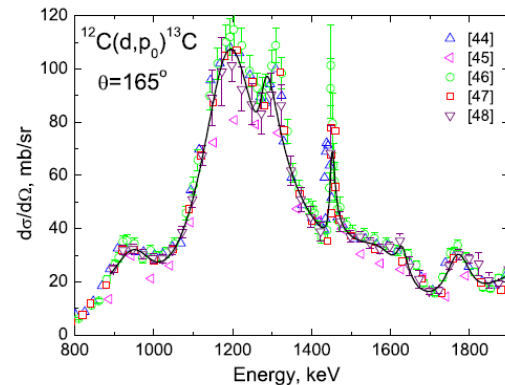
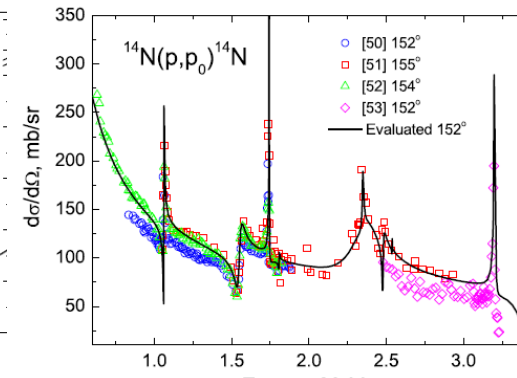
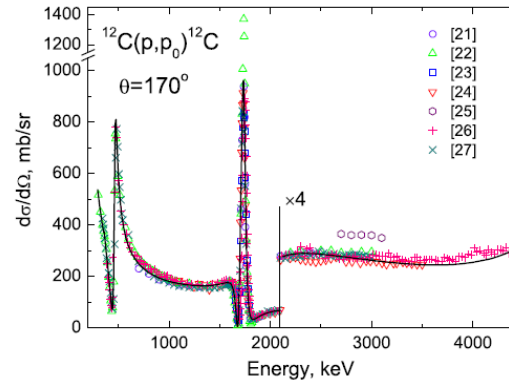
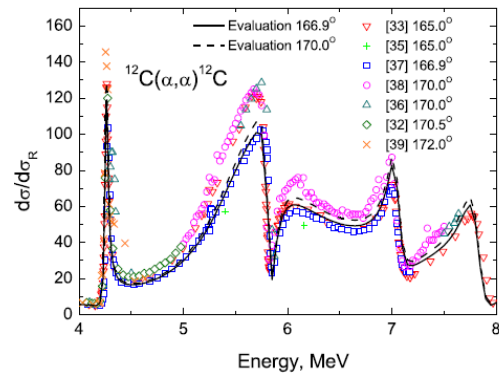
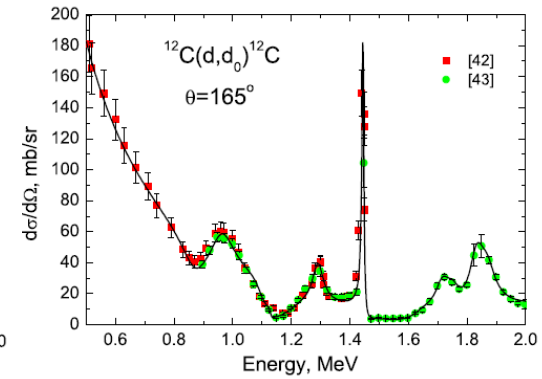
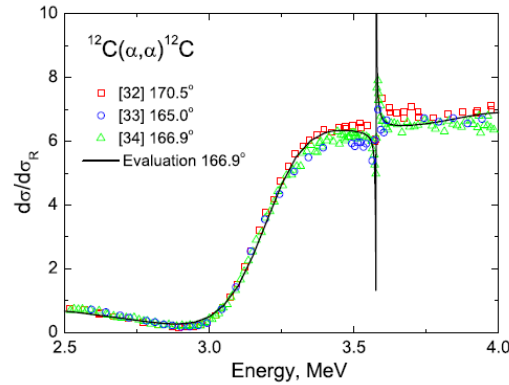
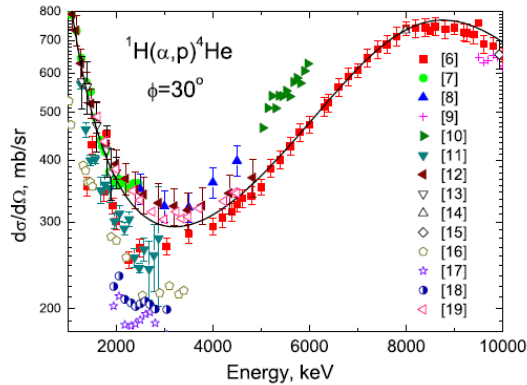
SigmaCalc scattering cross-sections for natural Mg (the isotopes behave differently) at two different scattering angles

*For **sharp resonances** one must correctly calculate energy straggling in depth (this effect can be **LARGE**)*

Barradas et al, NIM B247 (2006) 381

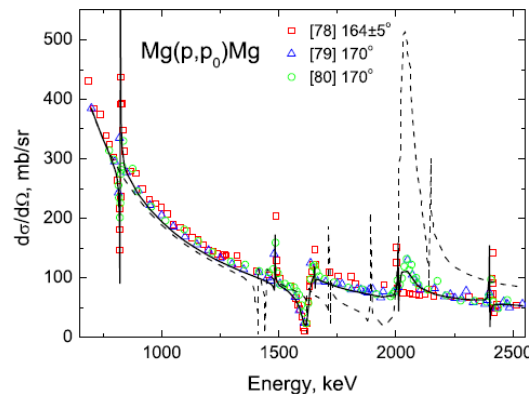
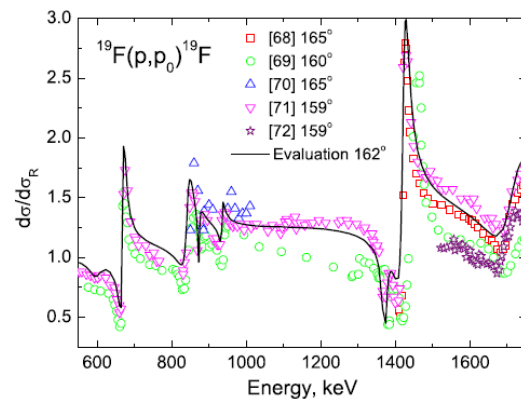
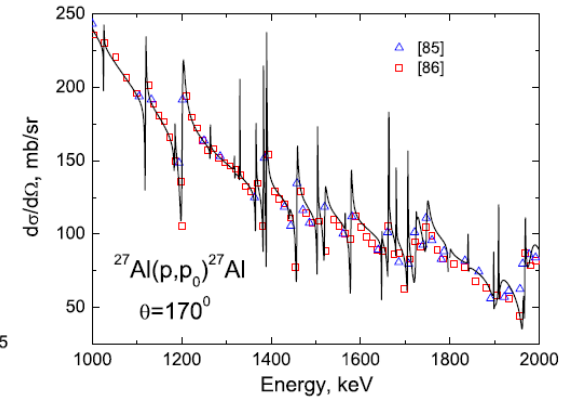
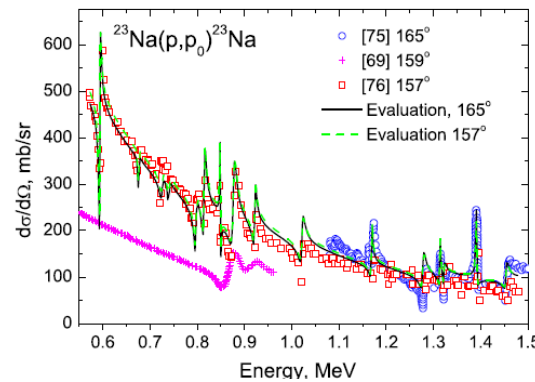
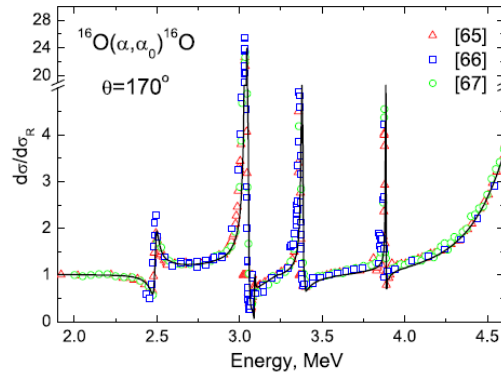
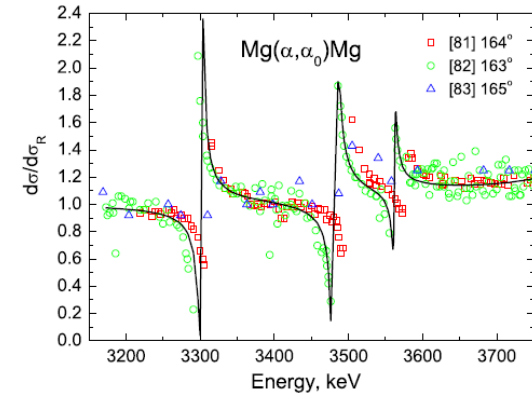
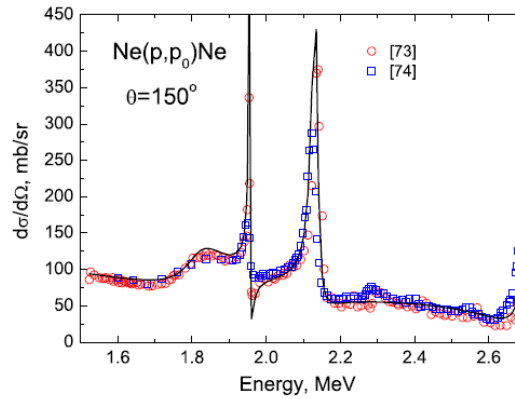
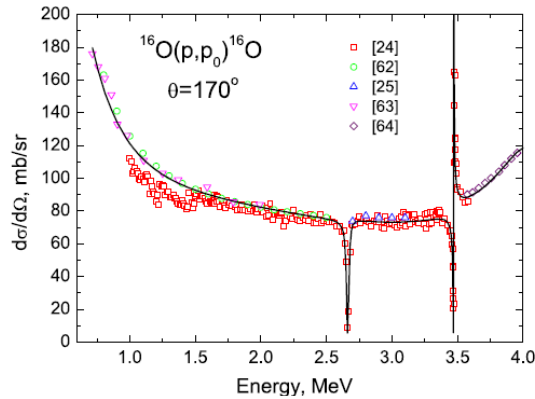
Previous Work: evaluations

A.F.Gurbich, Nucl.Instrum.Methods B, 268 (2010) 1703-1710



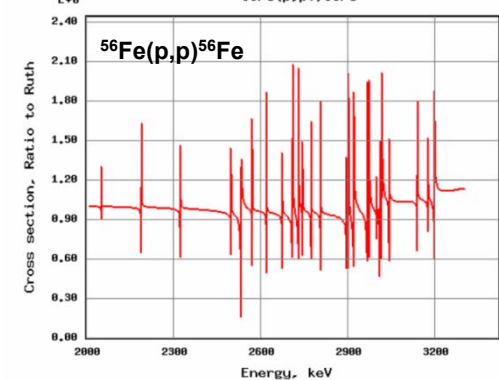
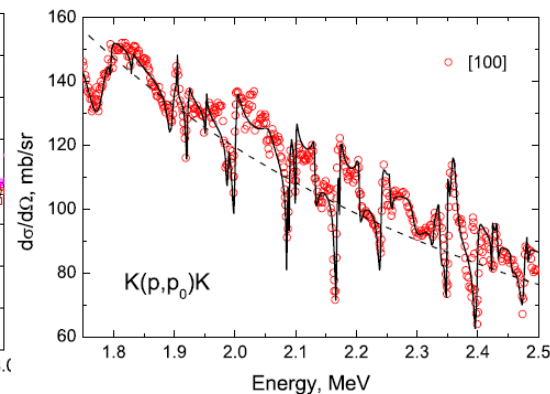
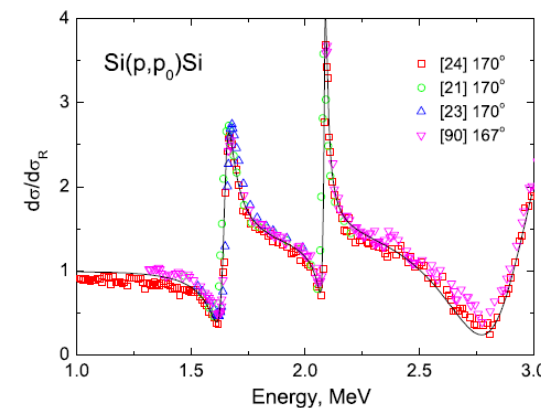
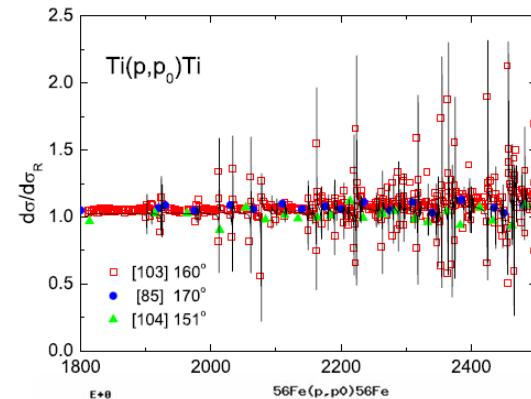
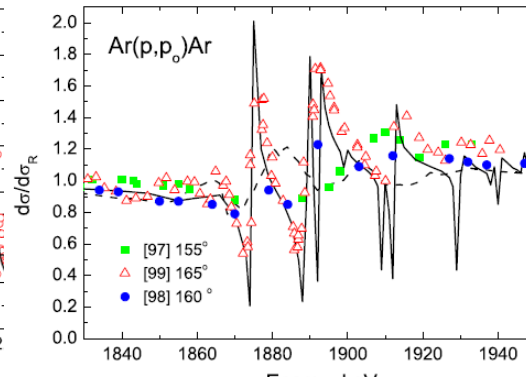
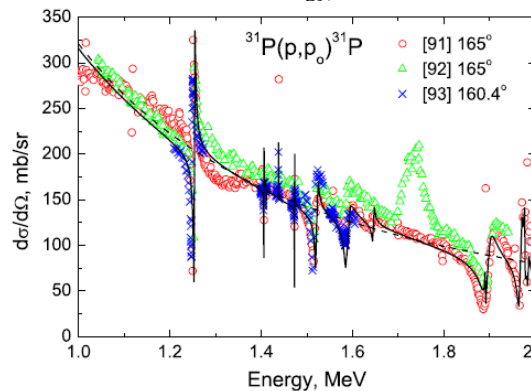
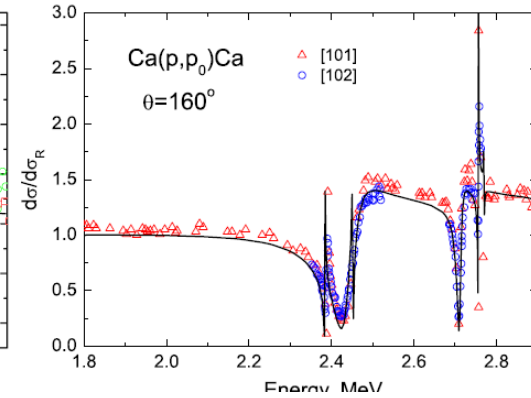
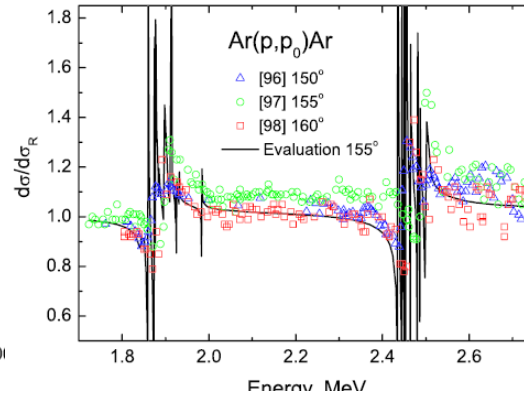
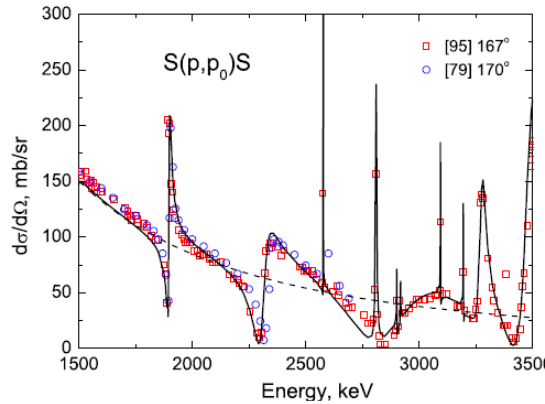
Previous Work: evaluations

A.F.Gurbich, Nucl.Instrum.Methods B, 268 (2010) 1703-1710

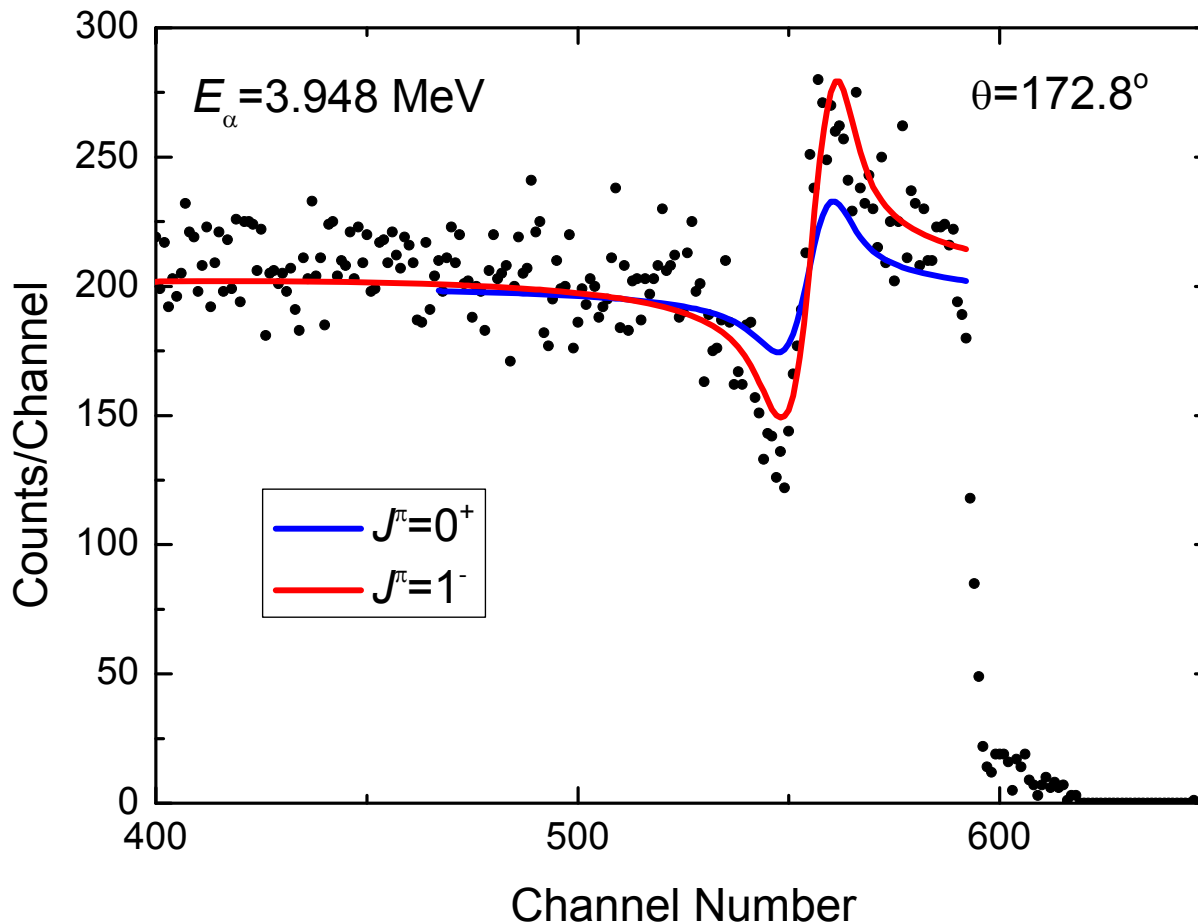


Previous Work: evaluations

A.F.Gurbich, Nucl.Instrum.Methods B, 268 (2010) 1703-1710



R-matrix modelling



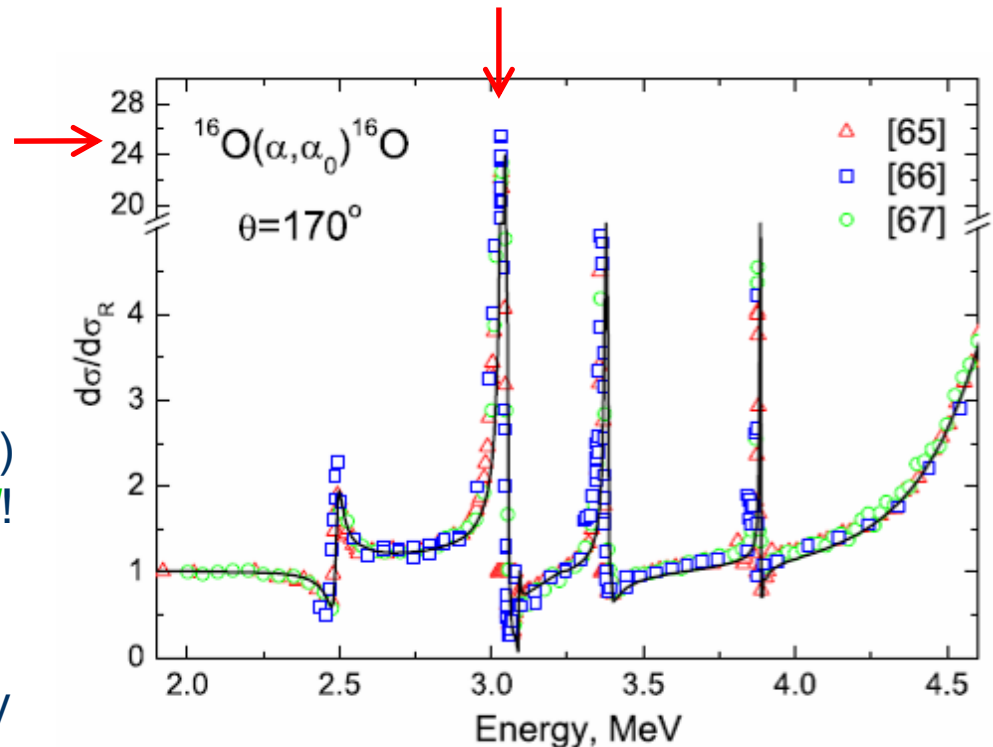
- **R-matrix** with formalism as before (Gurbich, 2008)
- Phase shifts use Saxon–Woods potential wells (not hard-sphere) to take into account **direct potential scattering**
- Data invites qualitative as well as quantitative fitting (J^π)

See: A.F.Gurbich, Evaluation of non-Rutherford proton elastic scattering cross section for nitrogen, *Nucl.Instrum.Methods B*, 266 (2008) 1193–1197

Finding the beam energy:

using EBS resonances as calibration points

- Schrödinger's equation solved for all open channels in nuclear scattering problem (see Gurbich 2010)
- Free parameters determined using nuclear data (including measured scattering cross-sections)
- For critical applications (where Uncertainty Budgets are constructed) **RBS** and **EBS** must be *distinguished*!
- Dramatically enhanced EBS sensitivities at resonances.
- Resonances can be used analytically where evaluated data exist.
- This resonance is at **3038±1 keV** (see current SigmaCalc)



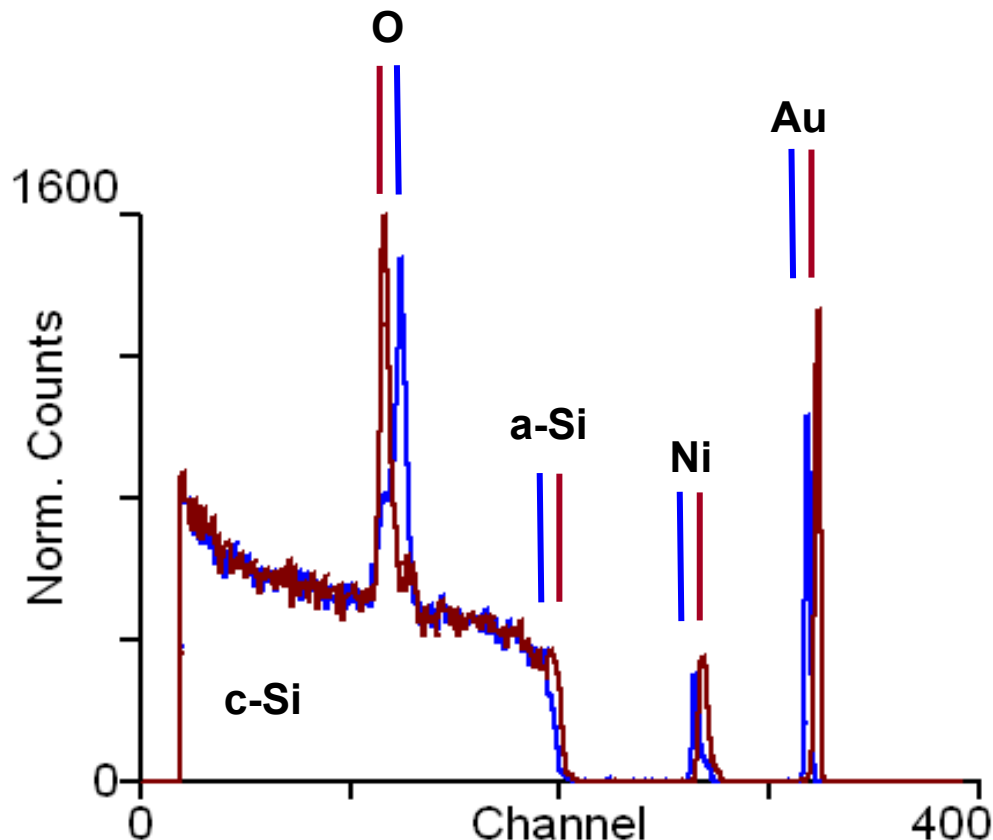
IBANDL (IBA Nuclear Data Library) :- www-nds.iaea.org/ibandl

SigmaCalc (evaluated cross-section on-line calculator) :- www-nds.iaea.org/sigmacalc

A.F.Gurbich, "The interaction of charged particles with nuclei", Chapter 3 in *2010 Handbook of Modern IBA* (Y.Q.Wang & M.Nastasi, eds, 2nd Ed., Pittsburgh: MRS)

Finding the beam energy

- Use Si\SiO₂\Ni\Au sample
- **Channel** to reduce background on O signal (not essential)
- **Gain** (hence **PHD**) determined *directly* by sample



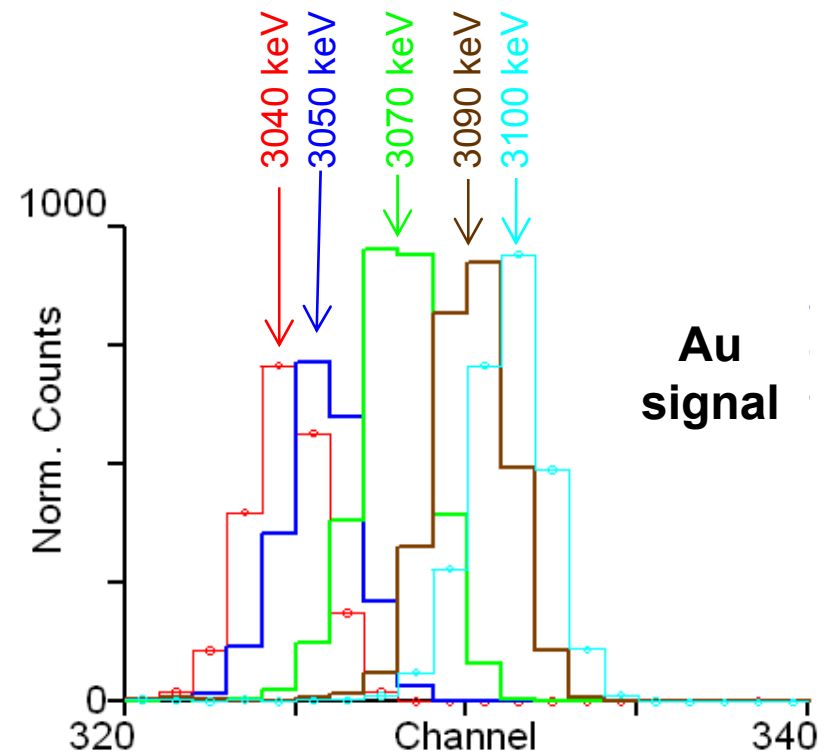
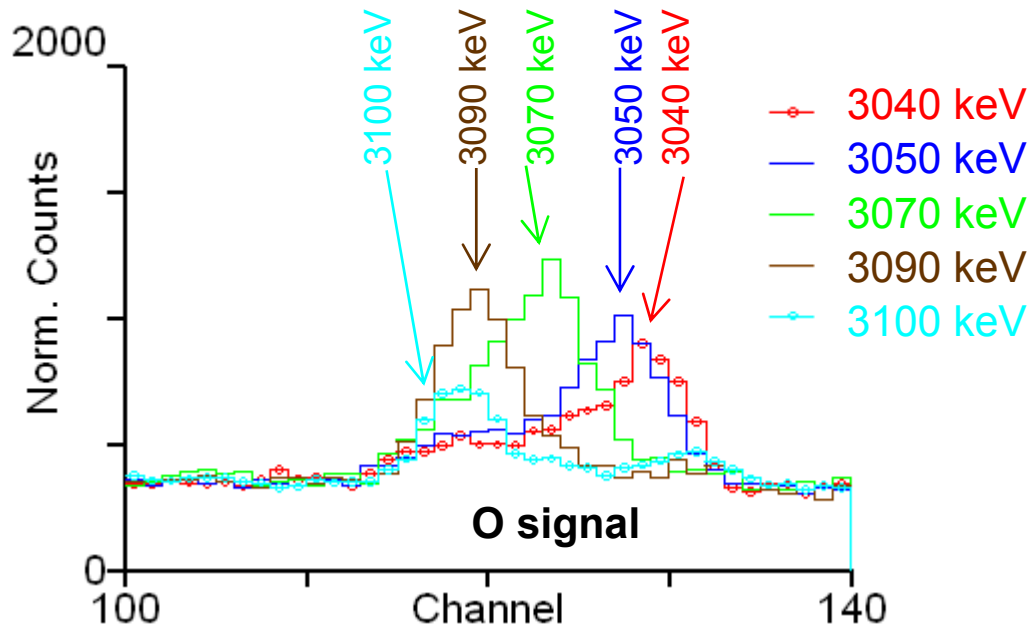
Spectra acquired at

3040 keV

3100 keV

Finding the beam energy

- Use Si/SiO₂/Ni/Au sample
- Channel to reduce background on O signal (not essential)
- Gain (hence PHD) determined *directly* by sample
- Multiple spectra at multiple energies
- Spectral shape determines energy (*fitting* in NDF)
- $^{16}\text{O}(\alpha,\alpha)^{16}\text{O}$ resonance at **3038±1 keV**



Finding the beam energy

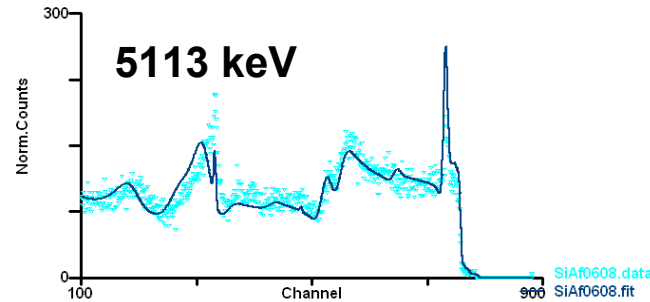
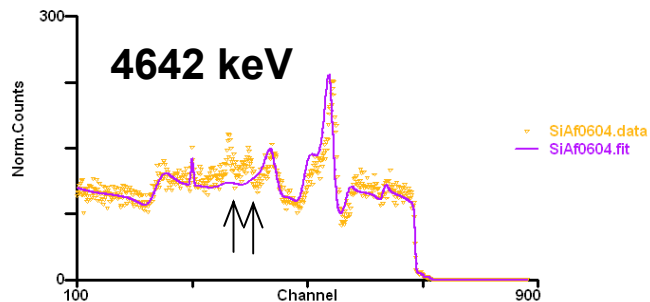
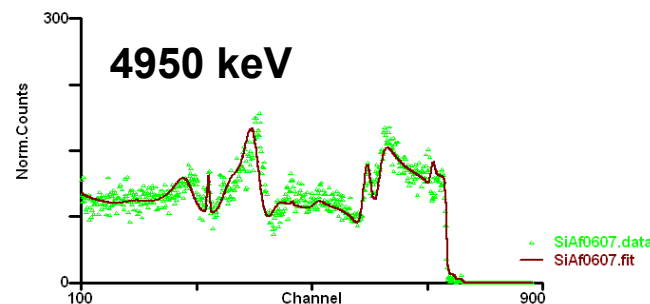
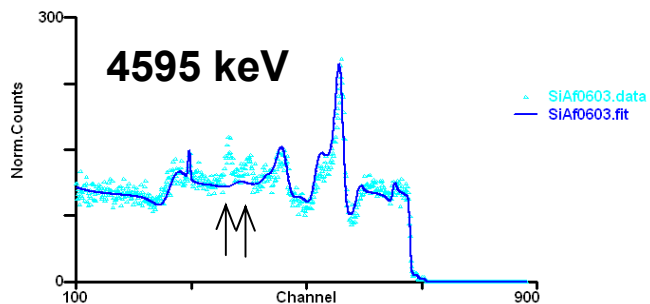
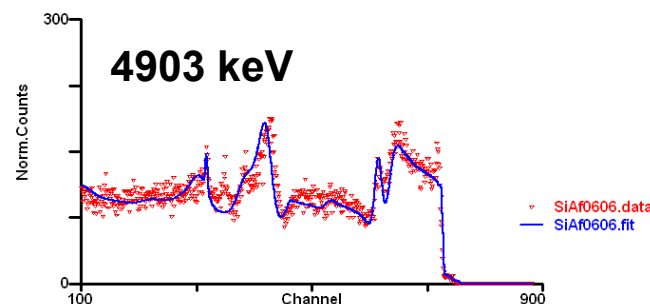
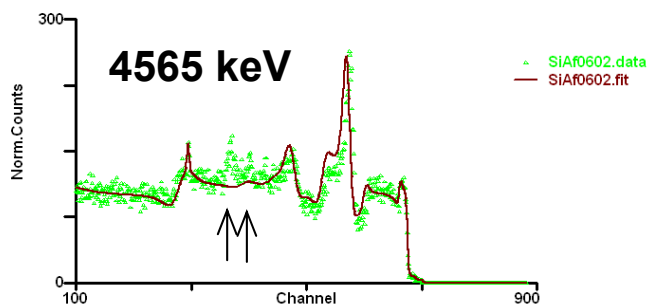
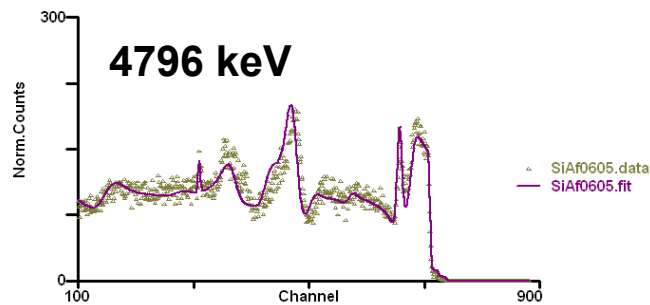
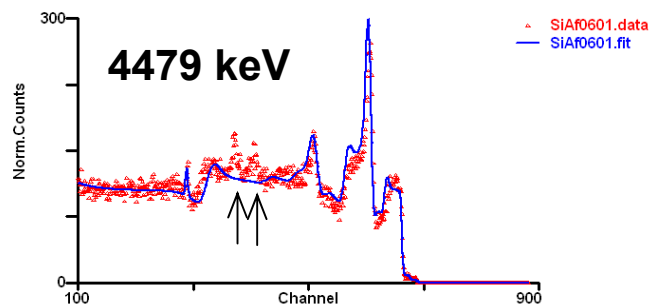
- DetA/DetB = **1 + 0.05%**. This is a **fitting bias**.
- DetA/DetB uncertainty is **0.03%**. This is a **fitting uncertainty**.
- Calibration factor uncertainty is **0.07%**. This can be interpreted as a **set-voltage uncertainty** of **1 kV** (or an energy uncertainty of 2 keV)

Nominal Voltage	Fitted			Ratio Det A / Det B	Calibration factor
kV	Det A (keV)	Det B (keV)	Average (keV)		
1495	3019.90	3020.00	3019.95	0.999967	1.0033
1500	3030.80	3030.10	3030.45	1.000231	1.0035
1505	3040.10	3039.60	3039.85	1.000164	1.0033
1510	3055.40	3053.40	3054.40	1.000655	1.0048
1515	3065.30	3063.60	3064.45	1.000555	1.0048
1520	3076.30	3073.50	3074.90	1.000911	1.0049
1525	3085.80	3083.30	3084.55	1.000811	1.0048
1530	3095.10	3093.20	3094.15	1.000614	1.0046
1535	3102.80	3102.20	3102.50	1.000193	1.0041
Average				1.000456	1.0042
St deviation				0.031%	0.065%

**NB: fixed gain
& PHD!**

Contents

- Introduction – Materials Analysis
- The $^{28}\text{Si}(\alpha, \alpha)^{28}\text{Si}$ reaction
 - *Why?*
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 - *Benchmarking*
 - *Results*
- Summary



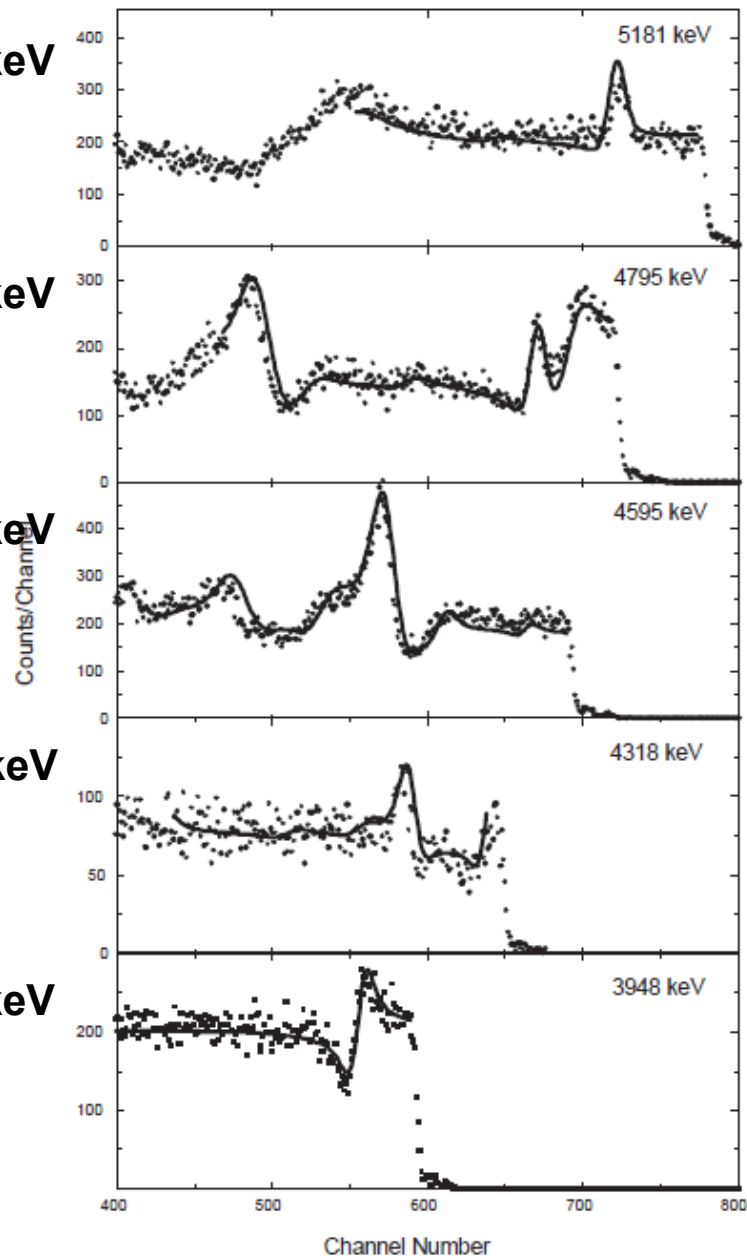
Set of data :-
2 detectors
~ 150° & 170°
78 energies
3717 – 6167 keV

Energy calibration:
3038 keV $^{16}\text{O}(\alpha, \alpha)$
4262 keV $^{12}\text{C}(\alpha, \alpha)$

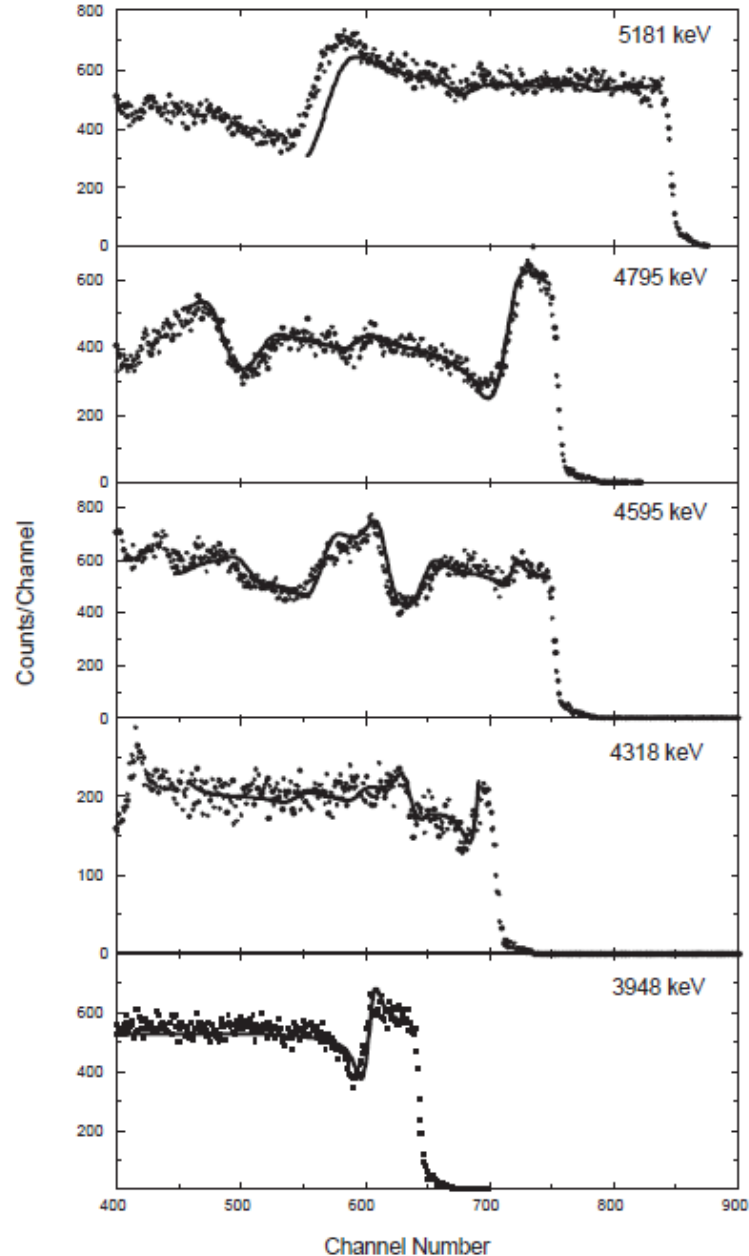
± 4 keV systematic
± 2 keV random

$\theta = 172.8^\circ$

5181 keV



$\theta = 149.2^\circ$



Results

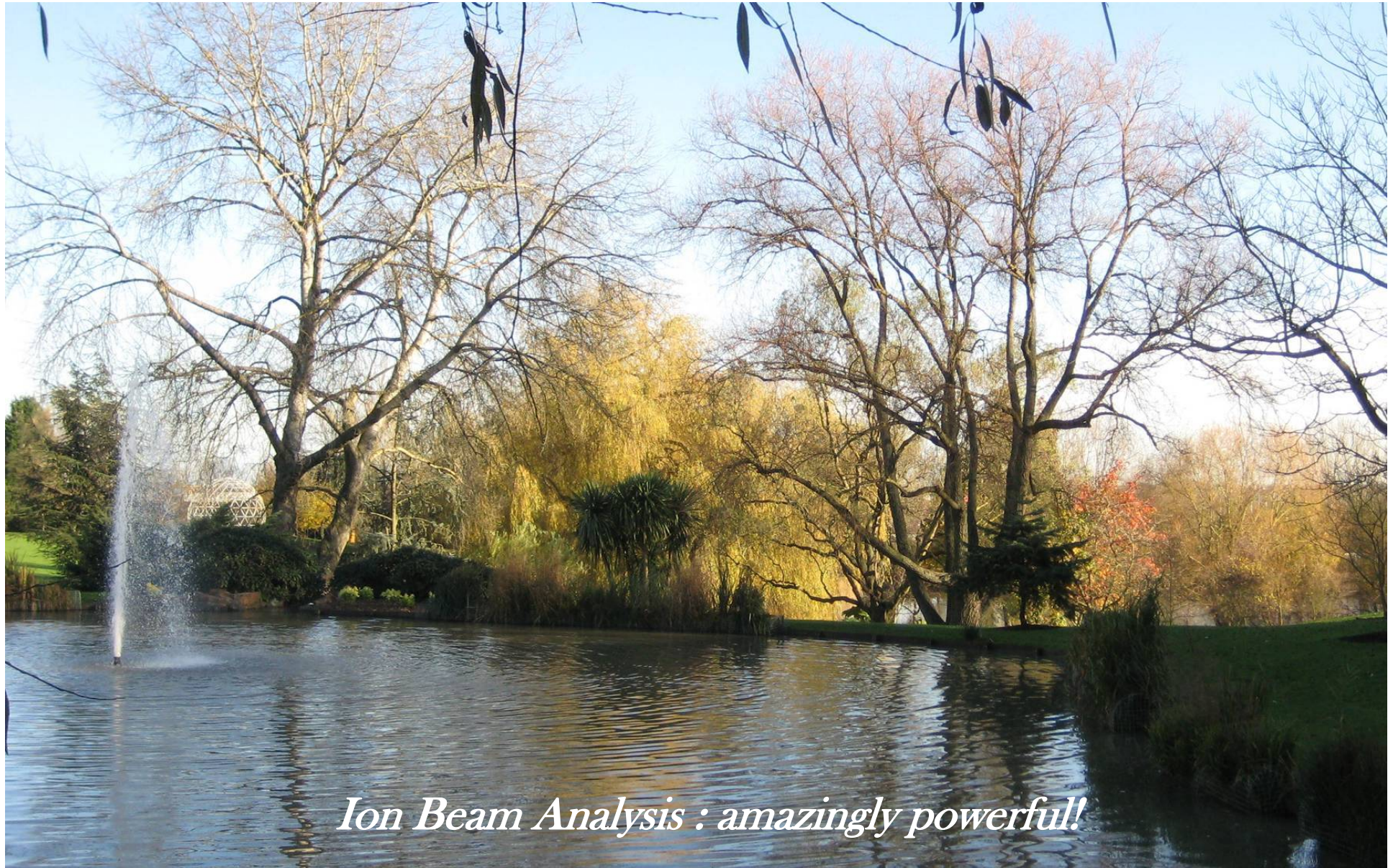
E_x (keV)			$J\pi$			Γ (keV)		
NPA 1990	NDS 2011	Surrey	NPA 1990	NDS 2011	Surrey	NPA 1990	NDS 2011	Surrey
10332	10369	10340	1-	(0+)	1-	6.1	5.8	3.6
10457	10500	10500	0+	(0+)	0+	1.7	1.7	1.7
10550	10570	10570	0	(0+)	0+	8	1.2	1.2
10701	10658	10623	1-	(1-)	3-	21	2.3	1.3
10769	10745	10718	2-	(0+)	0+	5.1	8.9	8.9
---	10816	10781		(3-, 5-)	3-		4.7	3.3
10826	10868	10824	1-	(2+)	0+	22	7.7	4.7
10916	10956	10921	1-	(0+)	0+	1.6	2.9	1.9
---	11107	11054		(2+)	0+		67.4	0.6
11140	11130	11166	1+	(0+)	5-	2.6	1.8	6.7
---	11254	11236		(3-)	2+		1.1	2.1
---	11410	11383		(3-)	5-		1.9	0.6

- **NPA1990:** P.M.Endt, *Nuclear Physics A*, 521 (1990) 1-830
- **NDS2011:** C.Ouellet & B.Singh, *Nuclear Data Sheets* 112 (2011) 2199-2355. These values in NDS2011 are based on K.-M.Källman, *Z. Phys. A*, 356 (1996) 287-291

Summary

- Accurate EBS cross-sections are:
 - *essential for IBA (PIXE + backscattering)*
 - *valuable also for astrophysics!*
- Evaluated cross-sections:
 - *Thin targets are best for making measurements*
 - *Thick targets are best for benchmarking*
 - *R-matrix fitting, Saxon-Woods absorption (not hard sphere)*
- Set of EBS spectra:
 - *Very accurate detector calibration valid for whole set*
 - *Very accurate 2 MV HVEE Tandetron calibration (4 keV systematic from known EBS resonances; 2 keV random from setting errors)*
 - *Correlation of all reactions reduces uncertainty*
 - *Ex, $J\pi$ and Γ values from spectral data*
 - *Values contradict NDS*

Thanks for listening!



Ion Beam Analysis : amazingly powerful!